



# Advanced Packaging Technologies

## Under Various Thermal Cycles

by

**Reza Ghaffarian, Ph.D.**

*NASA-JPL-CalTech*

(818) 354-2059

[Reza.Ghaffarian@JPL.NASA.gov](mailto:Reza.Ghaffarian@JPL.NASA.gov)



Copyright 2018 California Institute of Technology

Government sponsorship acknowledged

**NEPP Electronics Technology Workshop (ETW 2018)**  
**June 18-22, 2018, NASA GSFC**

**<http://nepp.nasa.gov>**

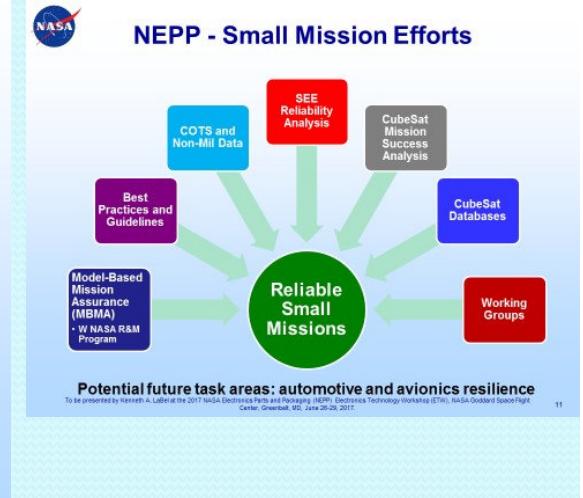
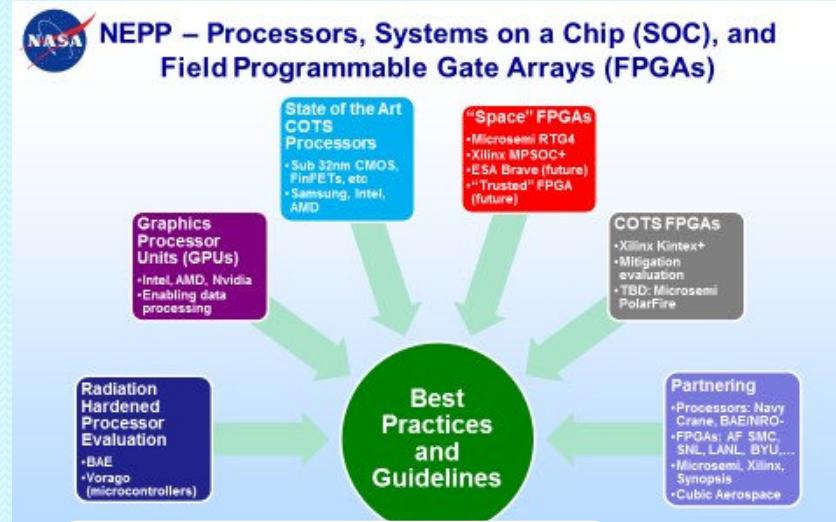
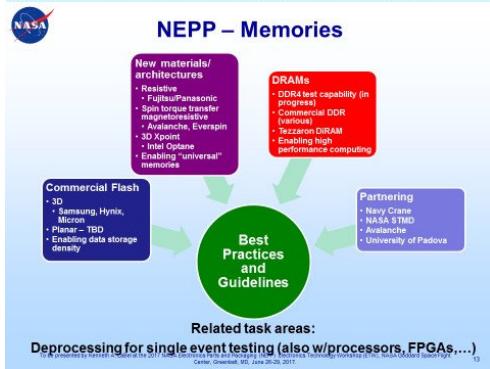


# Outline

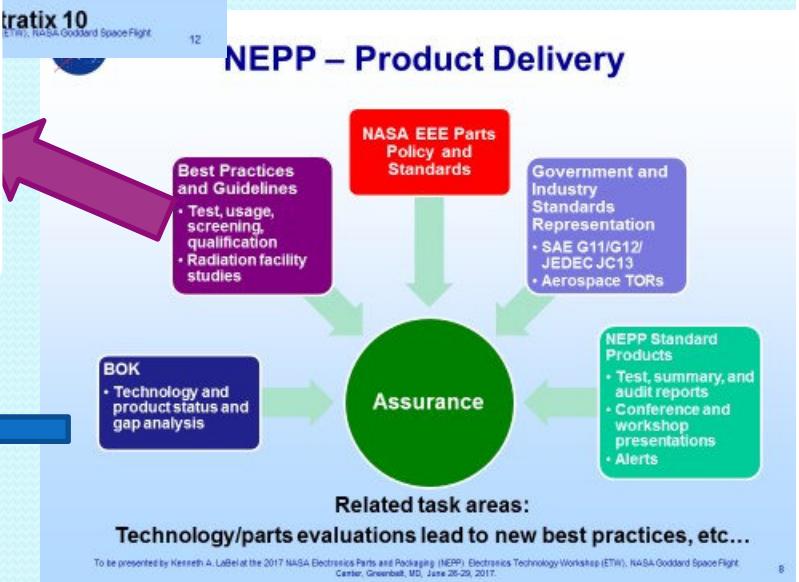
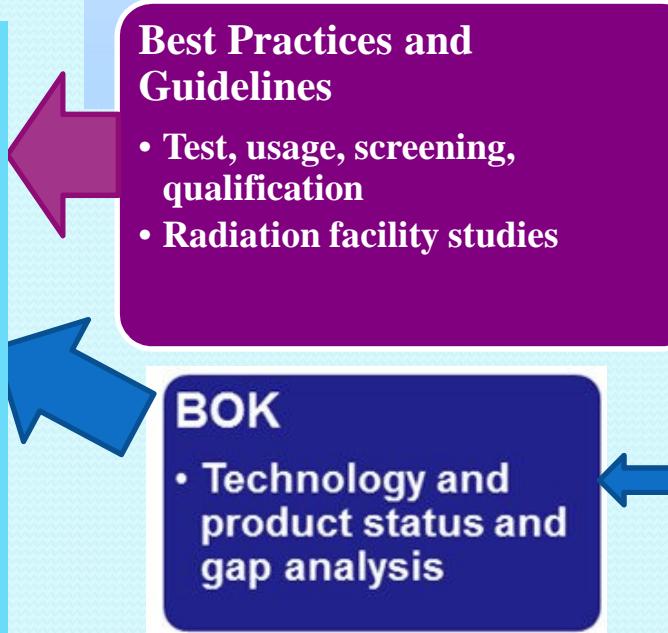
- Advanced Packaging Technologies
  - NEPP Tasks: FCBGA/TMV/WLP/TSV
  - Standard & WLP to Fan-out WLP (FO-WLP)
- Reliability under thermal stress
  - Creep/fatigue thermal stresses and combined stresses
- TC Reliability for Advanced Single Package
  - Test vehicle and advanced array packages
  - FCBGA1924 behavior under TC
  - FPBGA evaluation after TC
- TMV/2.5D (SiP)/3D/WLP TSV Evaluation
  - 3D memory TC evaluation
  - TMV test vehicle build and TC evaluation
  - System in package (SiP) and TC evaluation
  - WLP test vehicle design (FOWLP and 3D TSV)
- Summary



# FCBGA/TMV/TSV Packaging Technologies



**Test Results & BOK Guidelines NEPP Website**

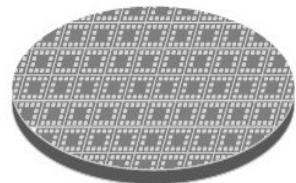




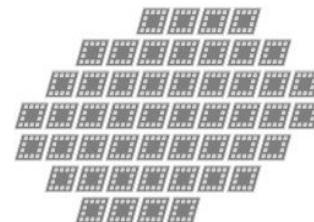
# Standard to FO-WLP Packaging Technologies

Standard  
Packaging

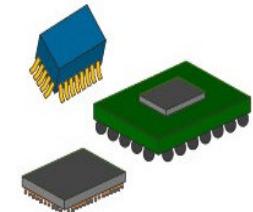
Silicon Wafer



Dicing

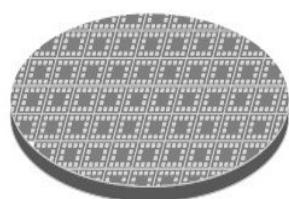


Packaging

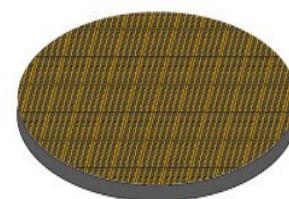


WLP  
Packaging

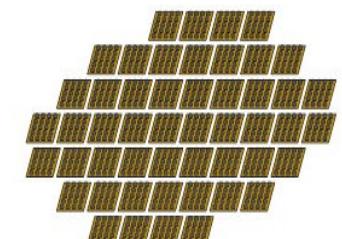
Silicon Wafer



Packaging

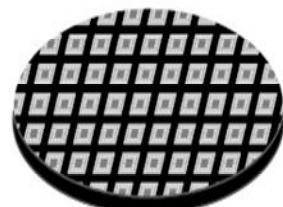


Dicing

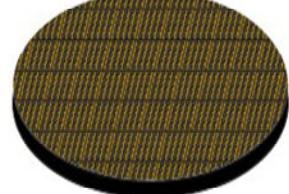


Fan-Out  
WLP

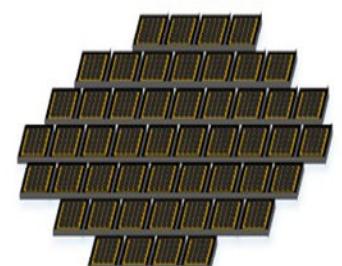
Reconstituted Wafer



Packaging



Dicing



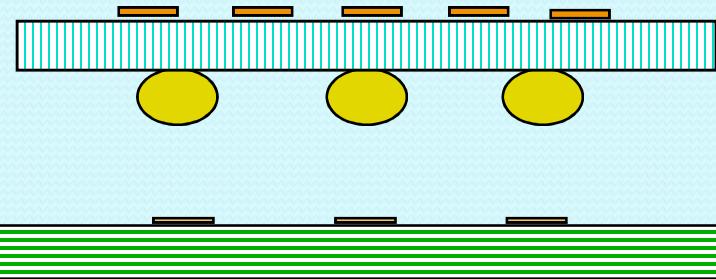


# Packaging Concept

- Chip node ~ 14 nm
- Die pitch ~ 150  $\mu$ m
- Al Pad- Non Reflow

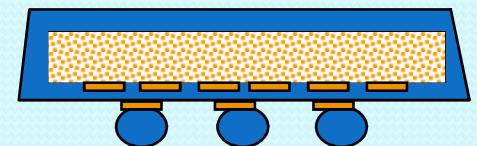


- Interposer
  - Polymer, Ceramic, Flex
  - Cu:Ni:Au Pad



- Norm pitch for PCB (> 0.3 mm)

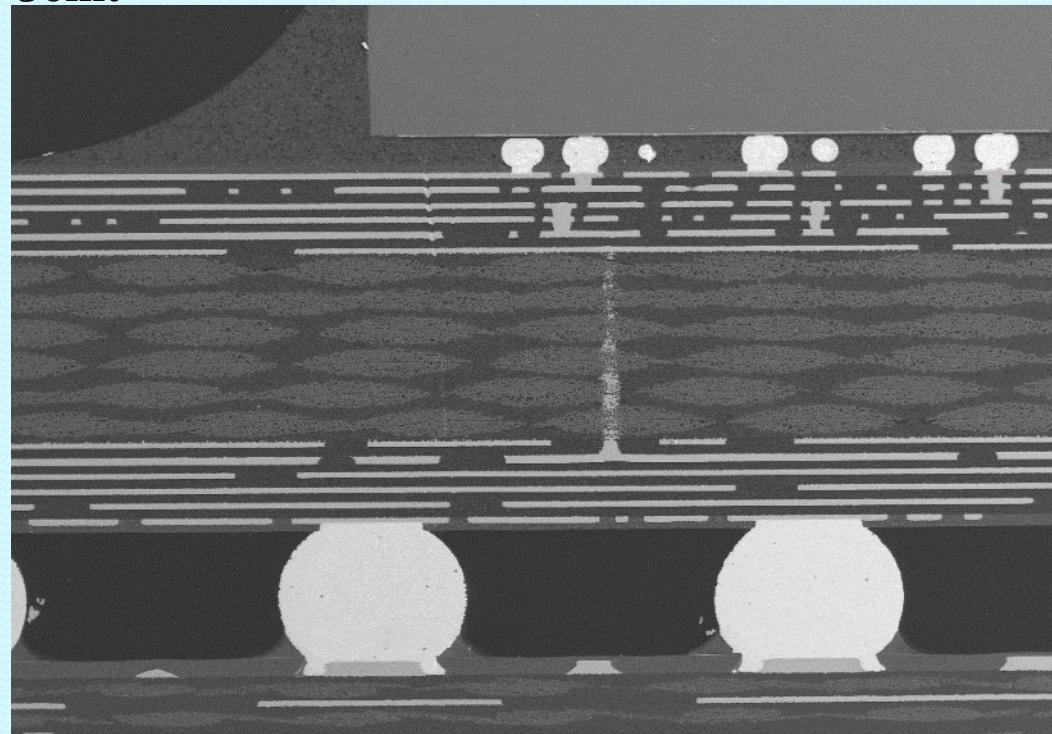
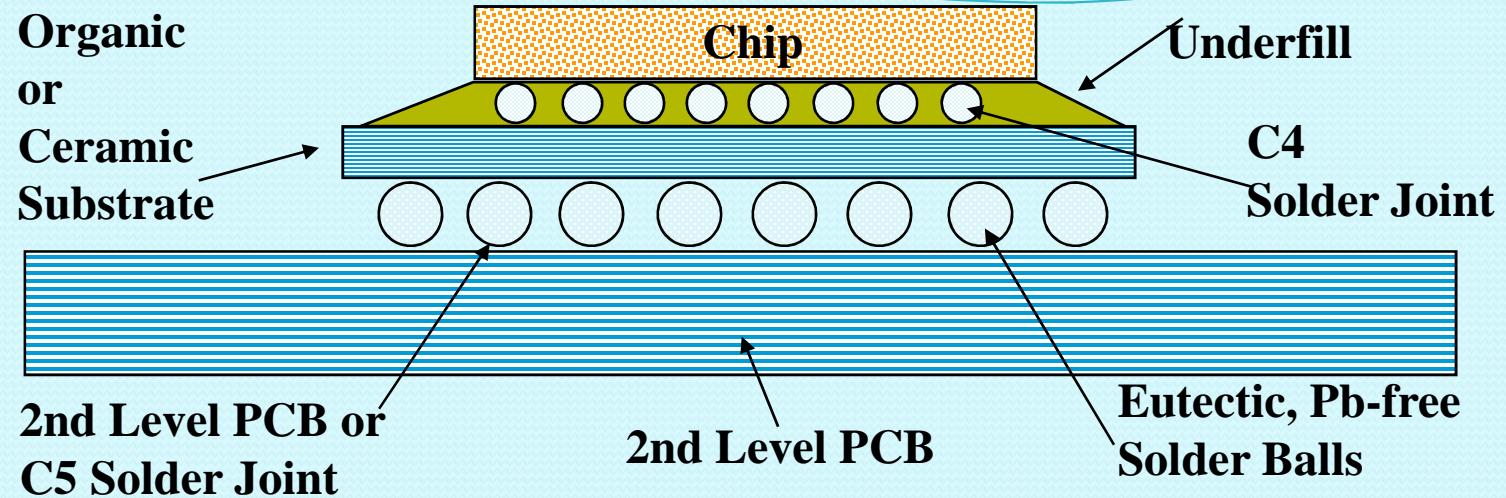
- Wafer
  - Pitch limitation
  - Mold & Fan-out





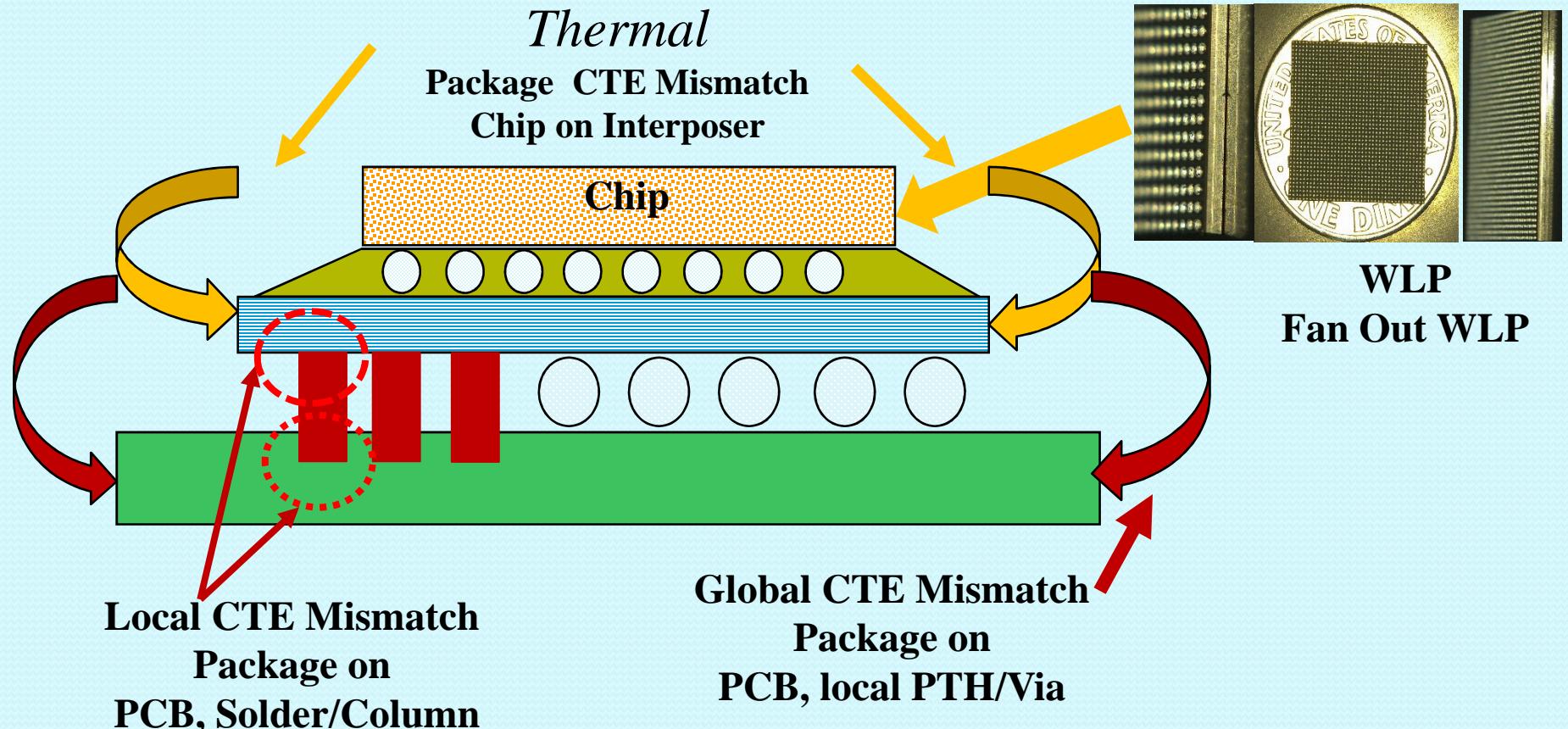
Jet Propulsion Laboratory  
California Institute of Technology

# Flip Chip BGA (FCBGA)





# Packaging Reliability Under Thermal Stress



$$\Delta D = (\alpha_c - \alpha_s)(T_c - T_0) L_D / H$$



# Fatigue Models Under TC

$$N_f(50\%) = \frac{1}{2} \left[ \frac{2\dot{\varepsilon}_f'}{\Delta D} \right]^m$$

$$\Delta D = (\alpha_c - \alpha_s)(T_c - T_0) L_D / H$$

Appears to be simple!

w/o

Physics of Failure (PoF)

**Model:** Semi-analytical, Semi-empirical

*New Approach*  $N_f \sim W^c$



# Accel TC for Solder

$$\Delta D = \Delta\alpha$$

$$\Delta T$$

$$LD/H$$

$$\Delta T = 0^\circ C \text{ to } 100^\circ C$$

***Creep (time dependent)***

$$\Delta T = -55^\circ C \text{ to } 100^\circ C$$

Creep + Fatigue

$$\Delta T = -55^\circ C \text{ to } 125^\circ C$$

Excess creep + Fatigue

$$\Delta T = -65^\circ C \text{ to } 150^\circ C$$

Excess creep + Fatigue

$$\Delta T = -120^\circ C \text{ to } 85^\circ C$$

Mild creep + Excess Fatigue

$$\Delta T = -196^\circ C \text{ to } 25^\circ C$$

***Low creep + Excess Fatigue***

**Note: New failure mechanisms when  
extreme hot/cold**



# Synergism TC+ Mech

$\Delta T + Vib + \Delta T$  for CBGA/CGA/PBGA

$\Delta T + Drop + \Delta T$  for CGA/FCBGA

Vibration at cold/hot for FPBGA/FCBGA/QFN

Vibration at hot for FPBGA/FCBGA

Vibration with  $\Delta T$  for FPBGA/FCBGA

T-V Sequence

$$CDI = \left( \frac{n_T}{N_T} \right)^{0.47} + \left( \frac{n_V}{N_V} \right)^{0.70}$$

V-T Sequence

$$CDI = \left( \frac{n_T}{N_T} \right)^{0.91} + \left( \frac{n_V}{N_V} \right)^{0.93}$$

A. Perkins: Solder Joint Reliability Prediction for Multiple Environments

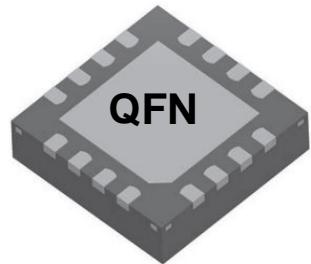
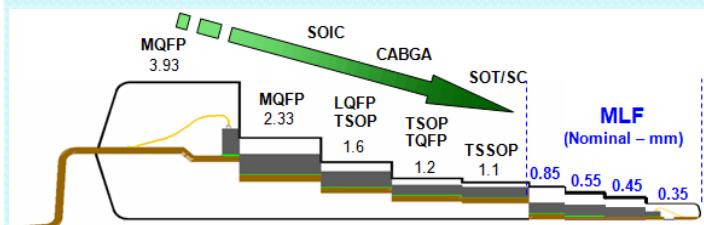
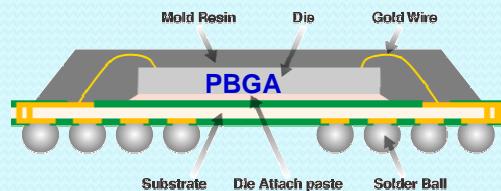
NEPP ETW- 2018

Reza Ghaffarian/JPL/Caltech

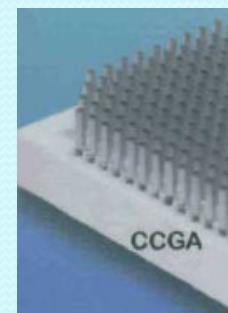


## Standard Single Chip Packaging

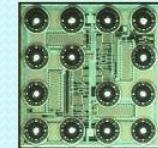
PBGA/SOC  
QFN/MLF



Wire bond to Flip Chip  
CBGA to CCGA

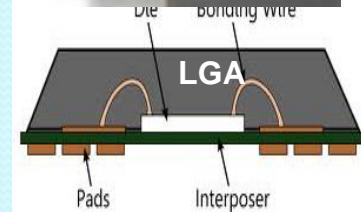
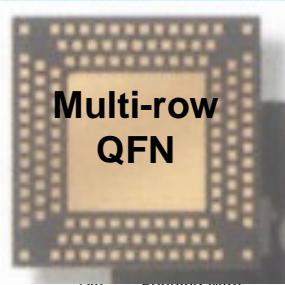


CSP / WLP  
a/M/W-  
QFN/LGA



Chip Scale  
Packaging  
(CSP)

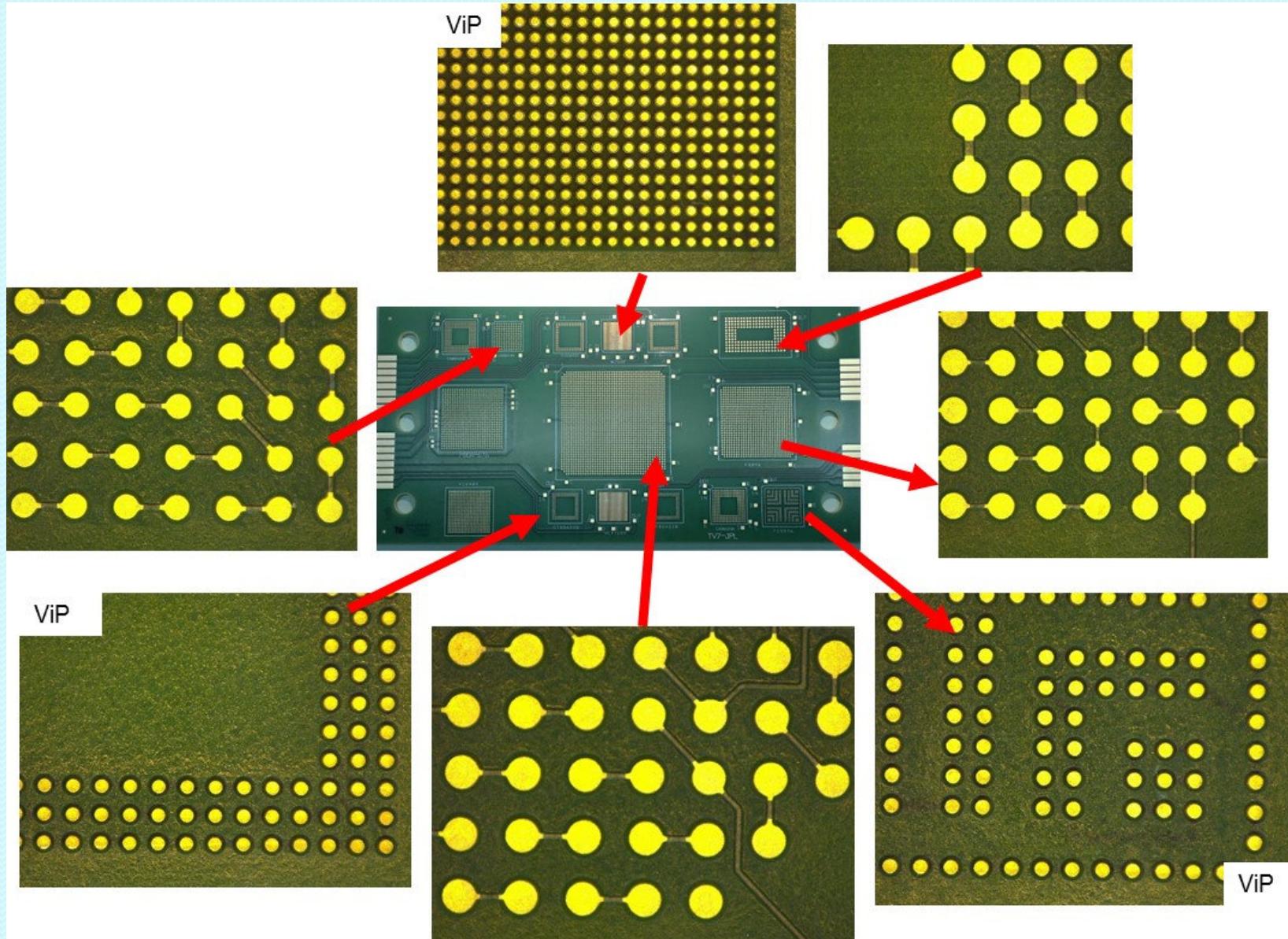
Wafer  
Level  
Packaging





Jet Propulsion Laboratory  
California Institute of Technology

# TC of Standard Packages





# FCCBGA/PBGA & more

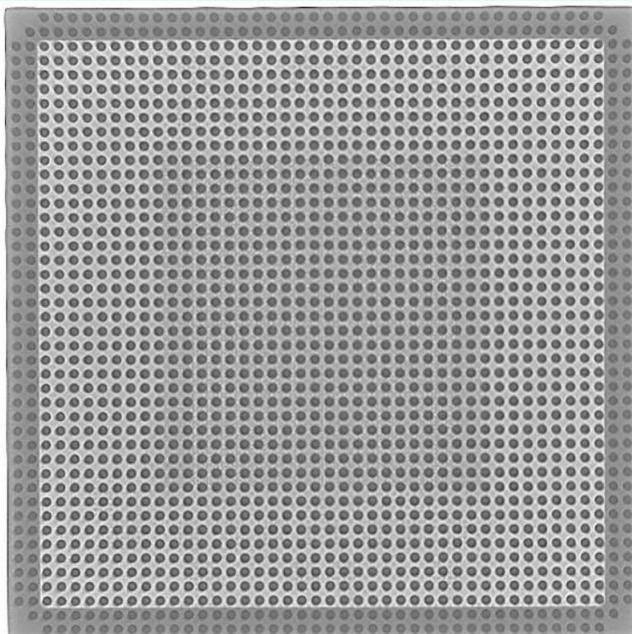
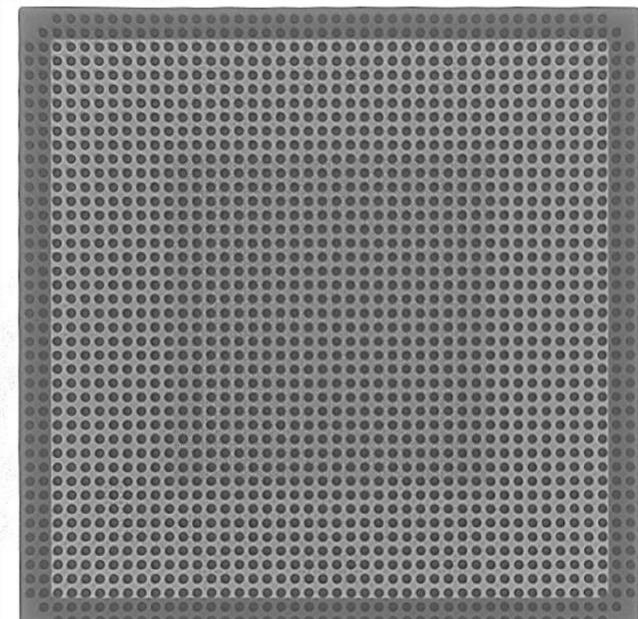
- Test matrix covered numerous standard packaging technologies
- FCBGA, FPBGAs, PBGAs daisy-chain package for TC reliability
- Two PCB finish (HASL/ENEPIG) W/WO Microvia
- Most single-side, one double-side mirror image
- TC= (-55°C/100°C), TC = (-55°C/125°C)
- TSC (-65°C/150°C)



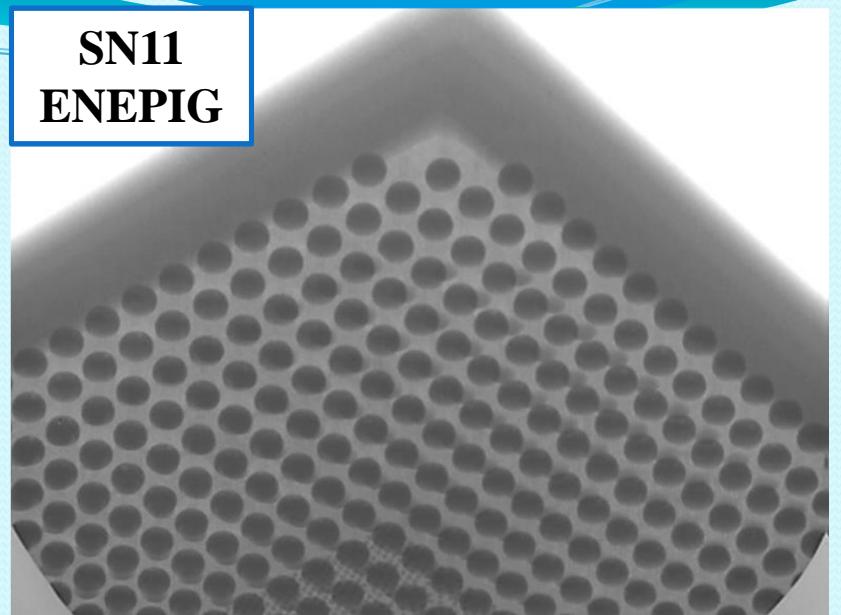


**Jet Propulsion Laboratory**  
California Institute of Technology

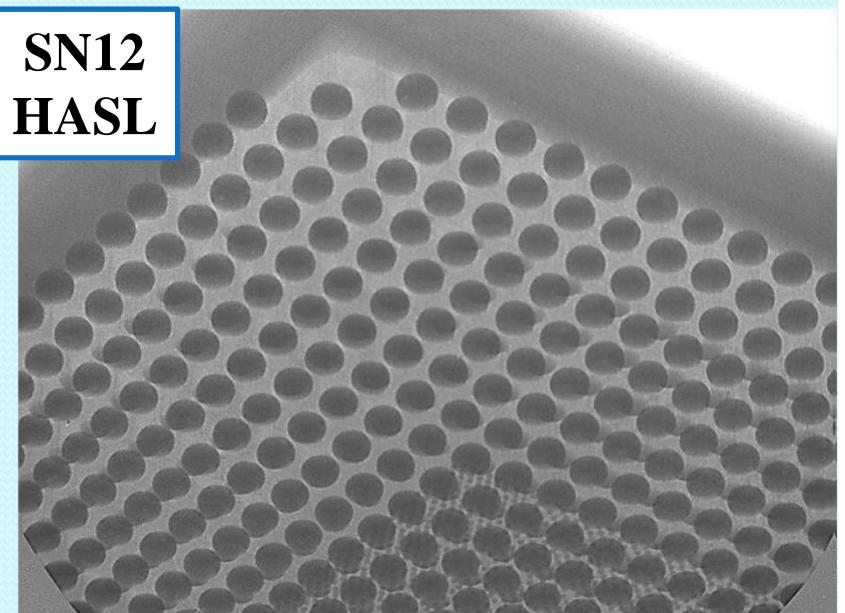
**X-ray  
FCBGA  
1924**



**SN11  
ENEPIG**



**SN12  
HASL**

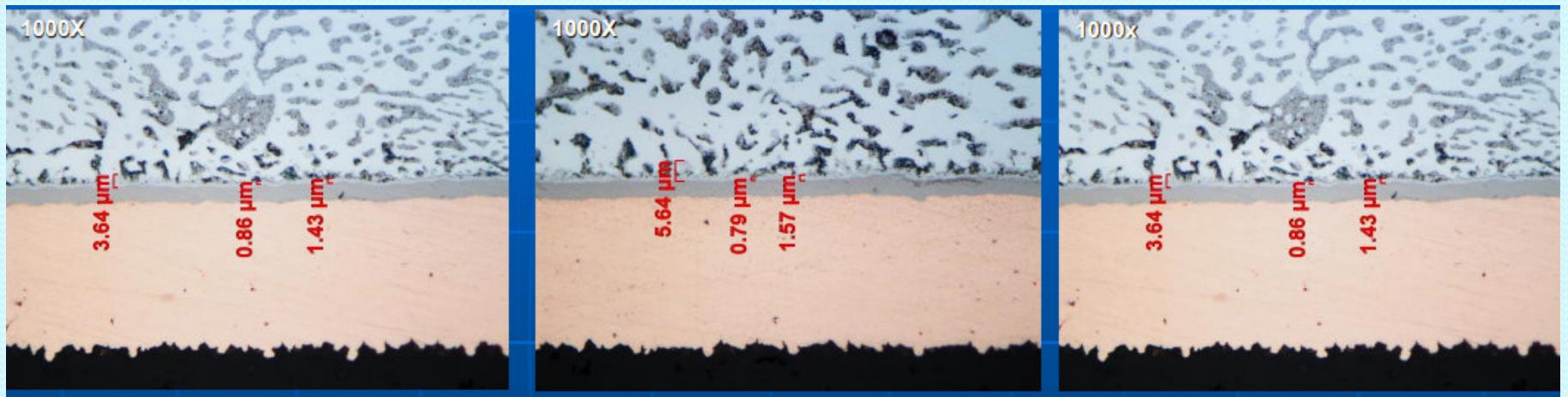
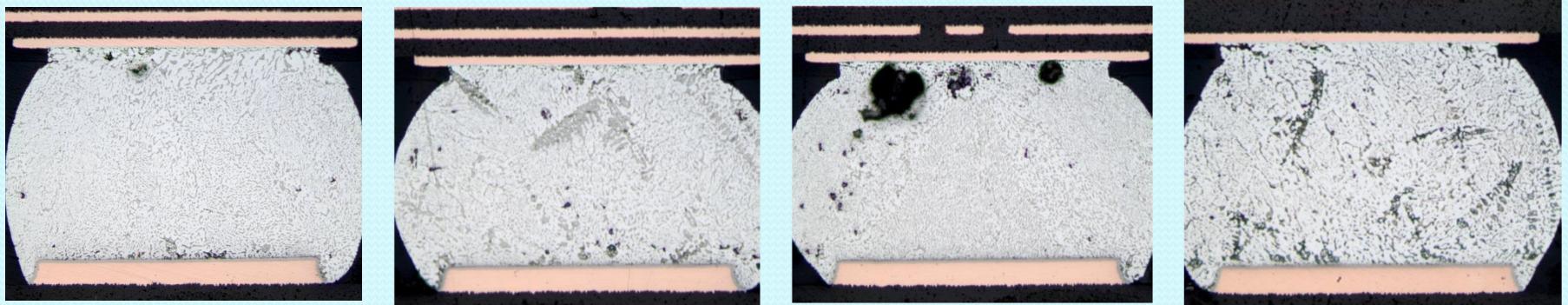




Jet Propulsion Laboratory  
California Institute of Technology

# FCCBGA 1924 on ENEPIG

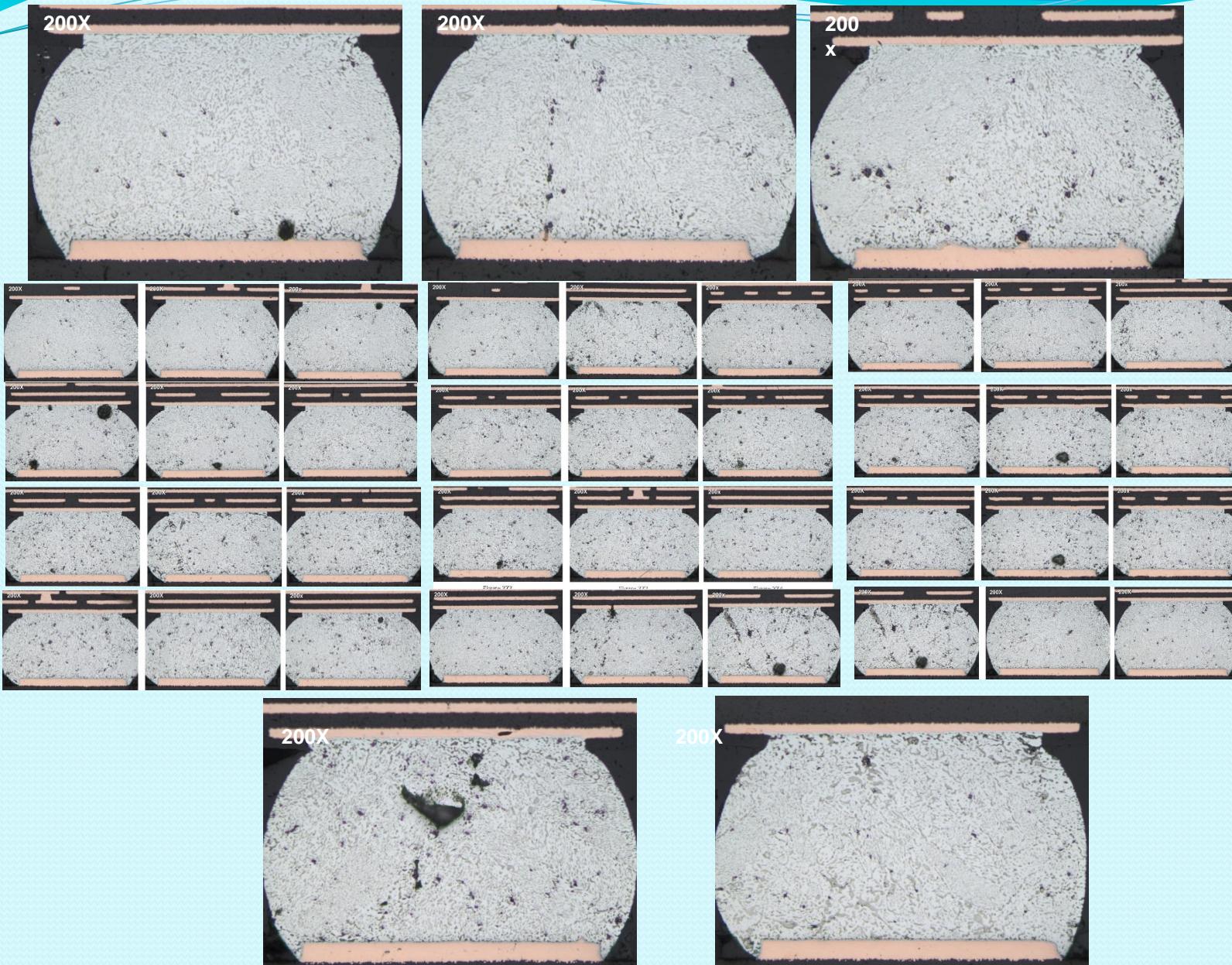
## 200 TSC (-65°C/150°C)





**Jet Propulsion Laboratory**  
California Institute of Technology

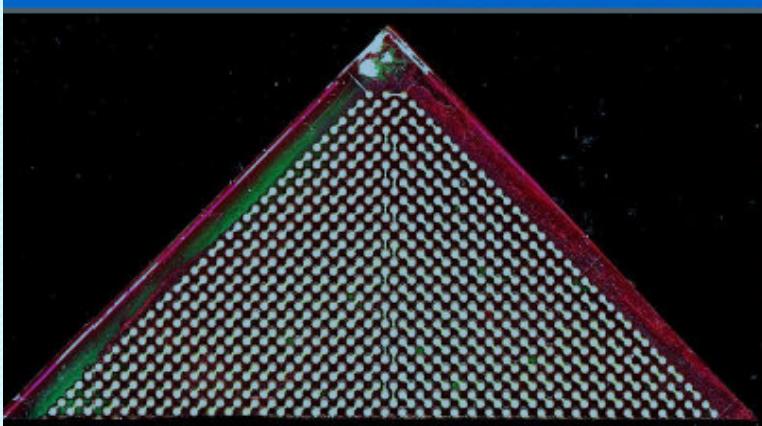
# FCBGA 1924 on HASL



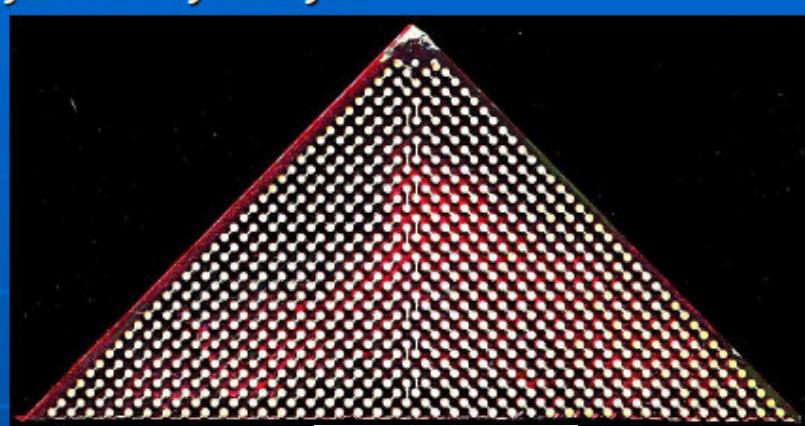


Jet Propulsion Laboratory  
California Institute of Technology

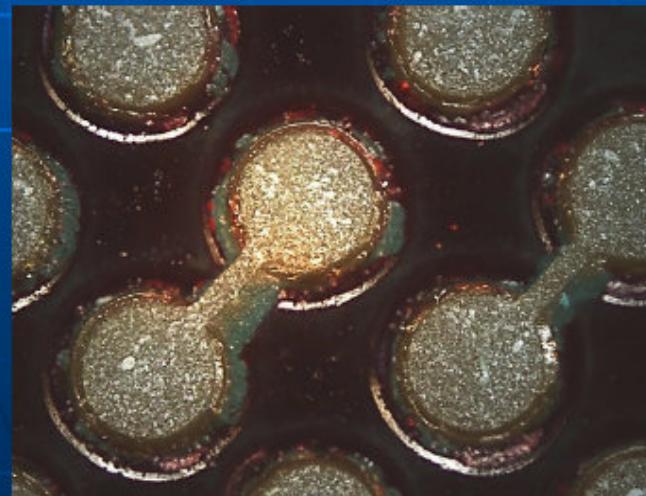
# FCCBGA 1924 on HASL 200 TSC (-65°C/150°C)



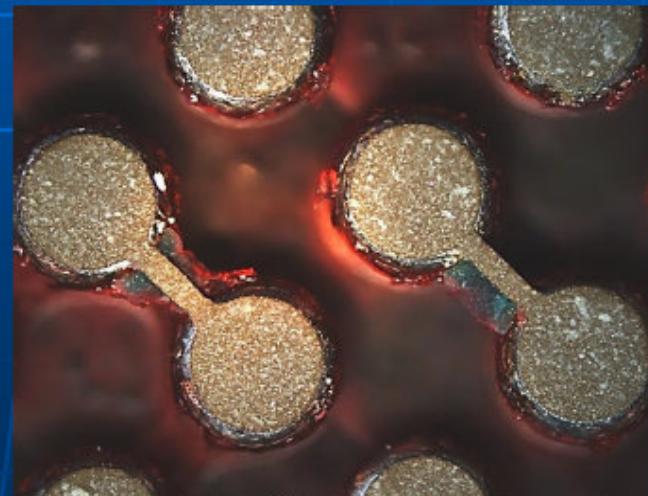
PCB Pads



BGA Pads



PCB Pads



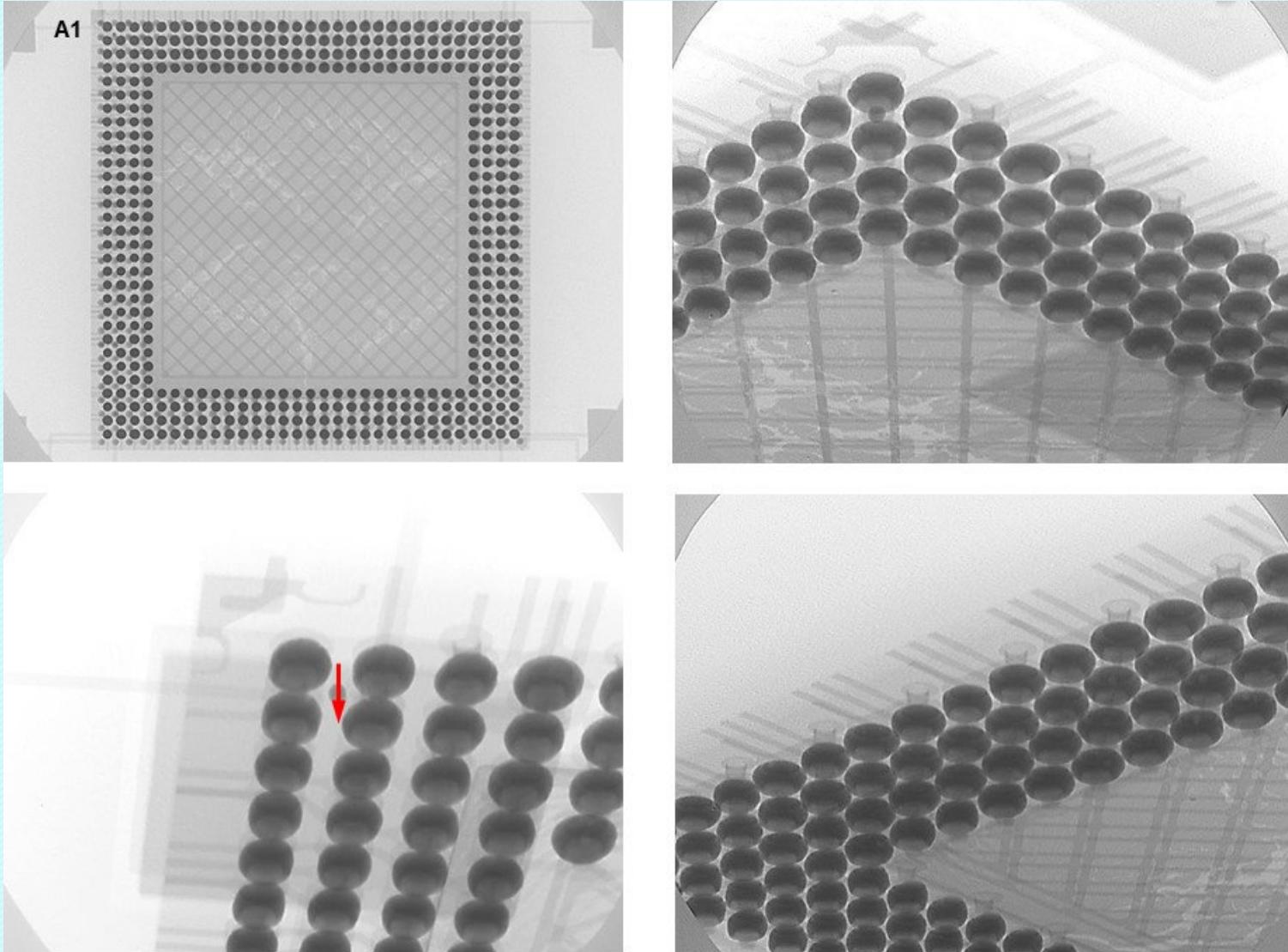
BGA Pads

No defective solder connections were found.



Jet Propulsion Laboratory  
California Institute of Technology

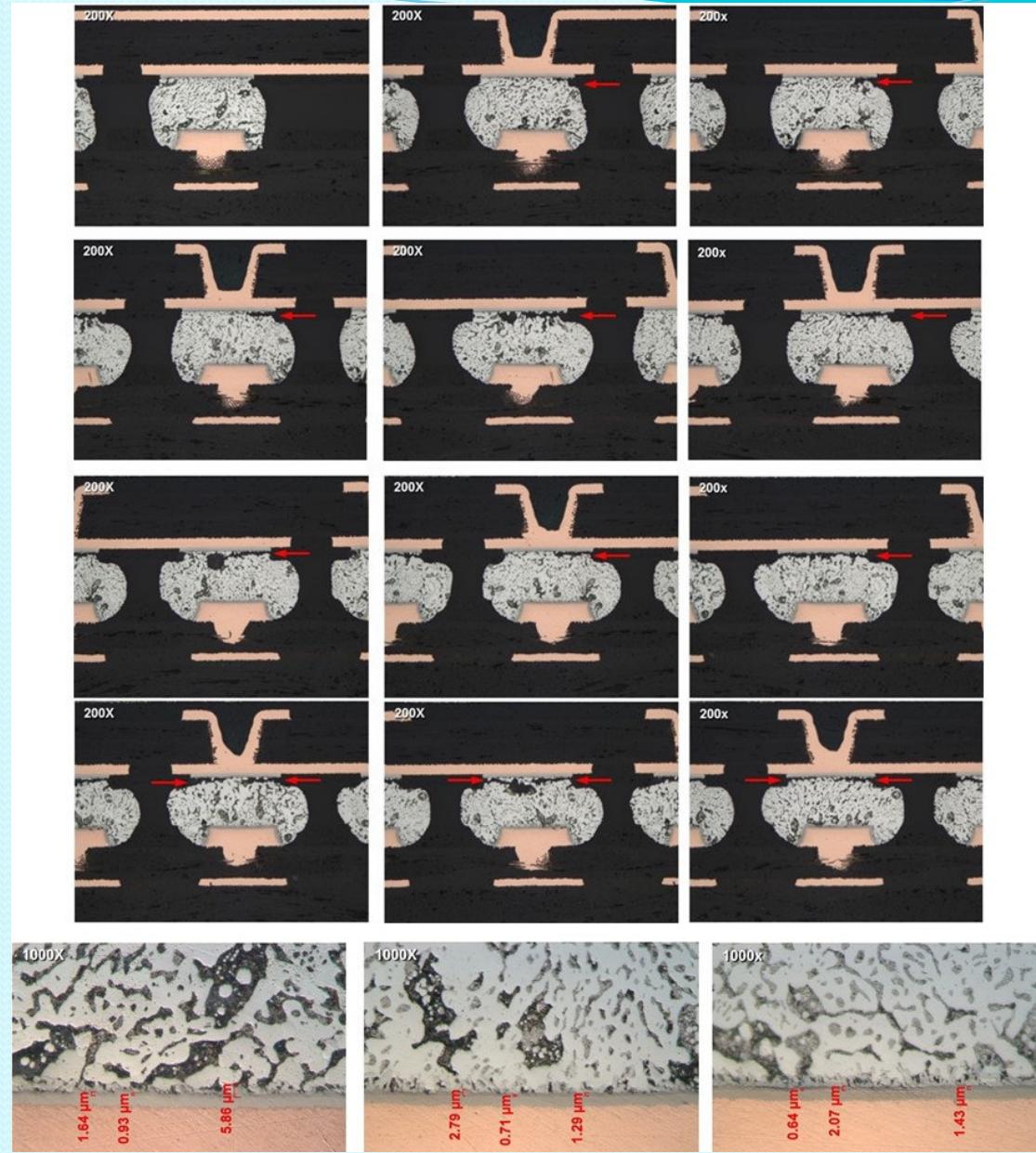
# X-ray FPBGA432/ENEPIG





Jet Propulsion Laboratory  
California Institute of Technology

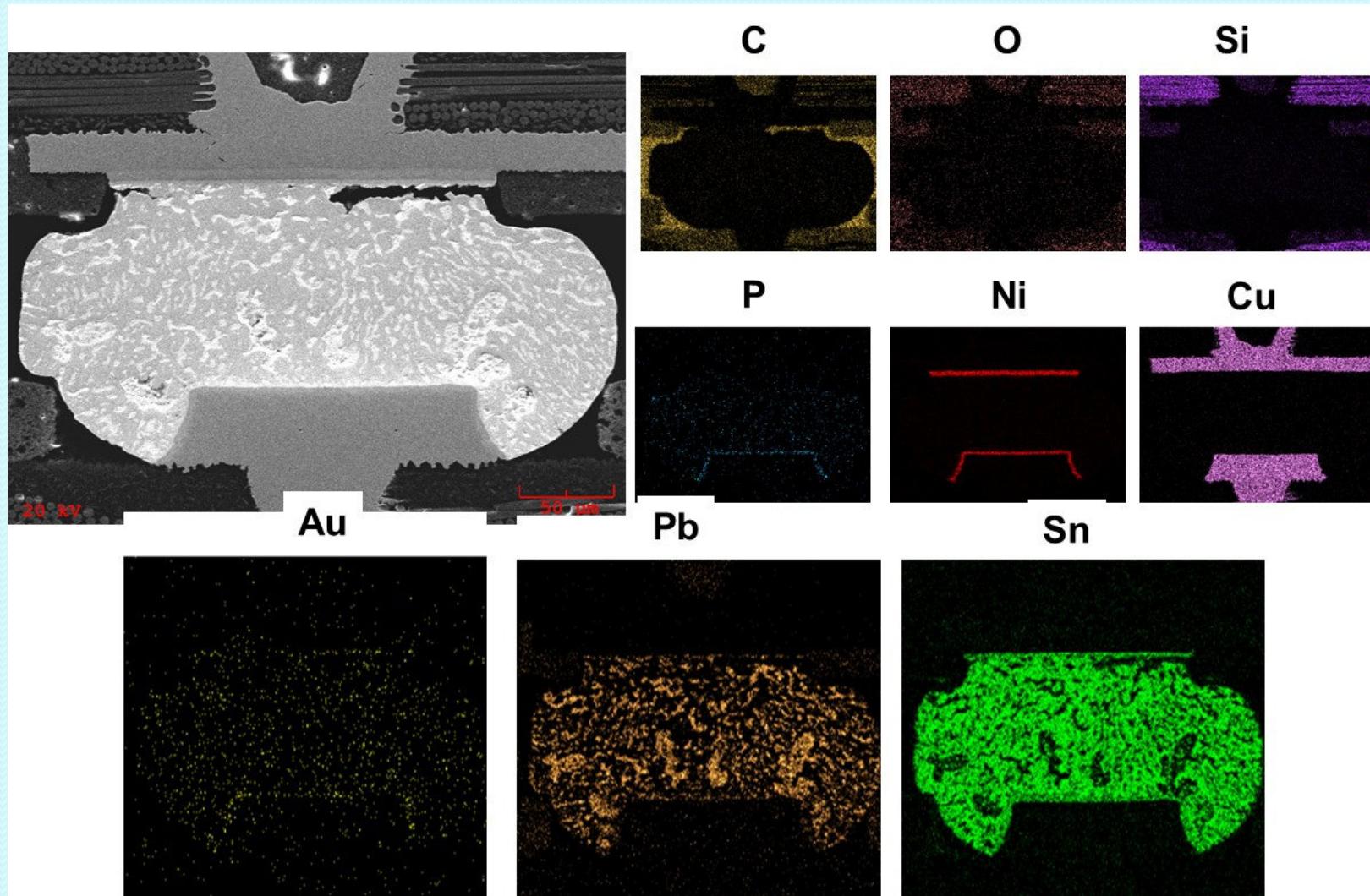
# FPBGA432 on ENEPIG





Jet Propulsion Laboratory  
California Institute of Technology

# SEM/EDS of FPBGA432 on ENEPIG PbSn Balls



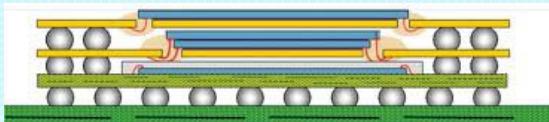


## 2.5D/3D

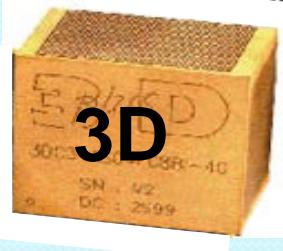
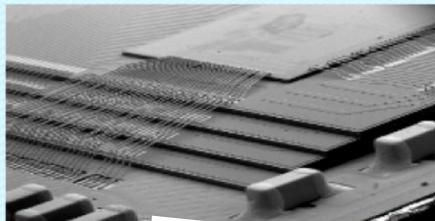
### Packaging Technologies

Stack Die  
PoP

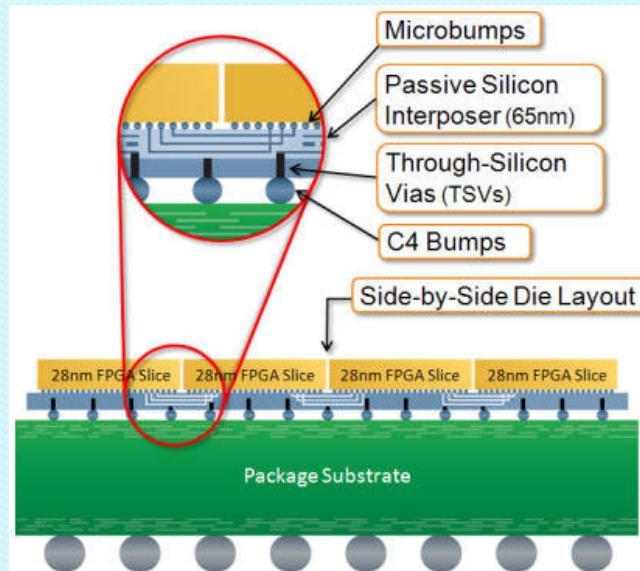
#### Package on Package (PoP)



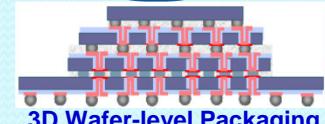
3D Wire Bond



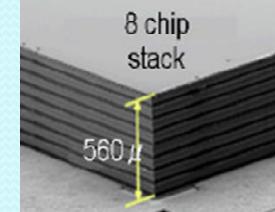
*2D to 2.5 D\**  
*Single Chip to Multi-chip*  
*TSV for Interposer*



2.5D to 3DTSV  
3D SIP

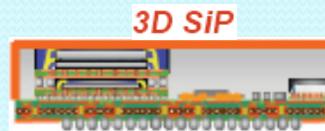


3D Wafer-level Packaging

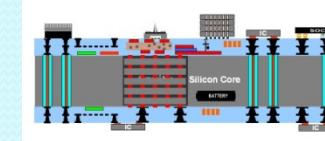


8 chip stack  
560  $\mu$

Through-silicon Via



3D SiP

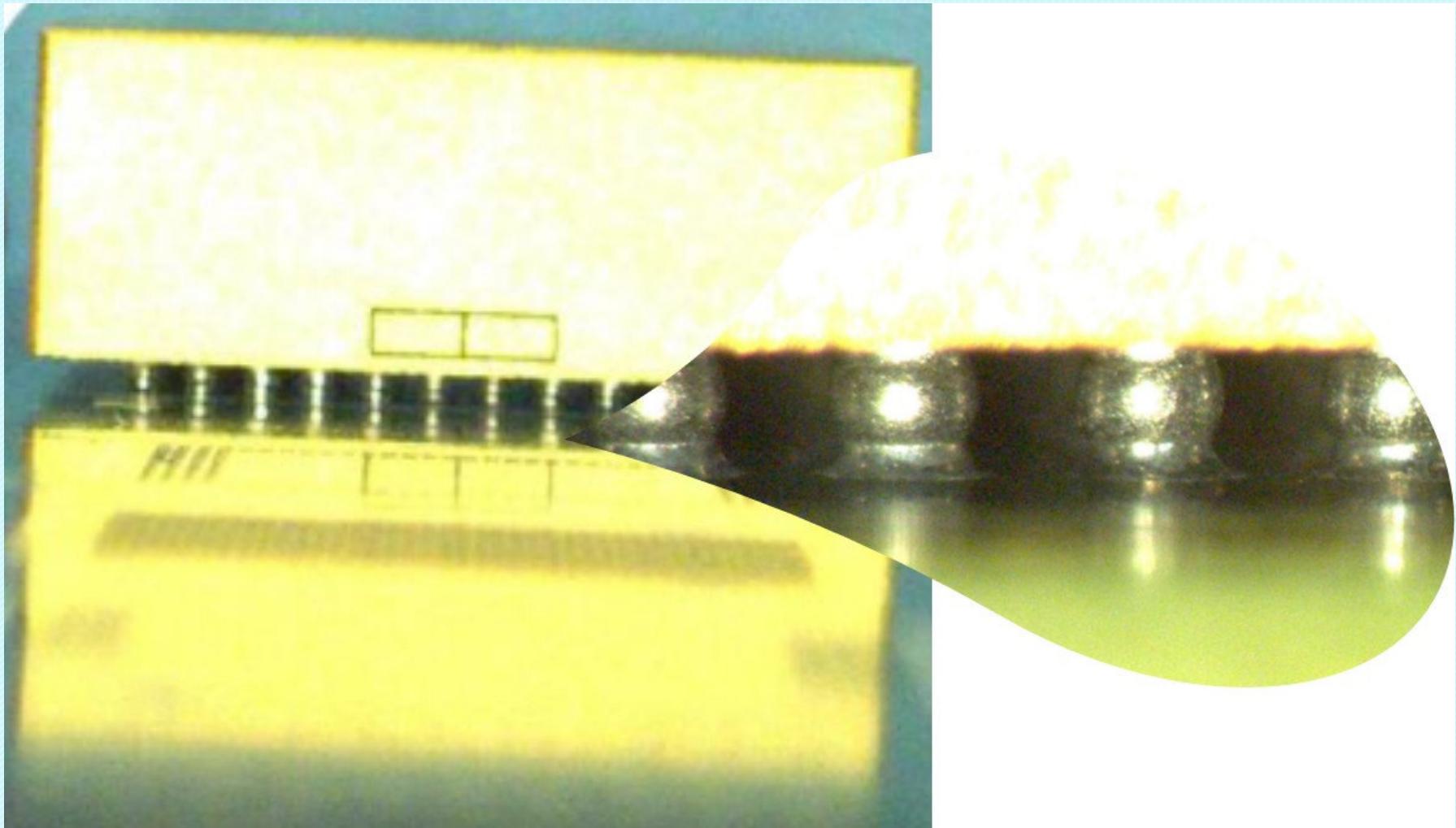


\* 2.5D now 2DS (on silicon substrates) and 2DO (on organic substrates)



Jet Propulsion Laboratory  
California Institute of Technology

# 3D Stack Single-sided





Jet Propulsion Laboratory  
California Institute of Technology

# 3D Stack

## X-ray after TC

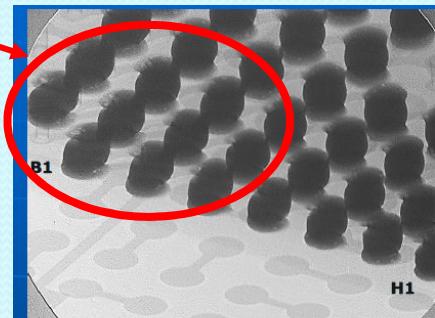
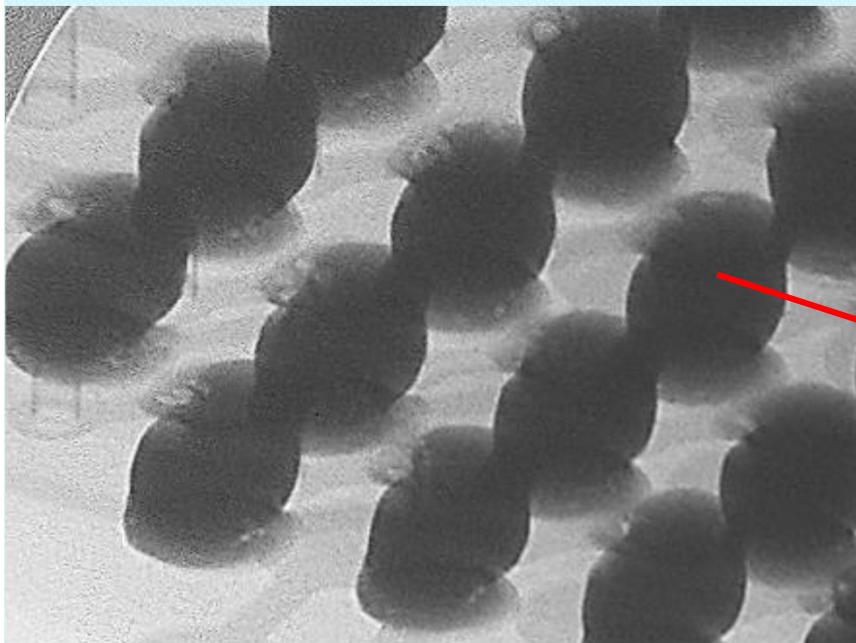


Figure 8  
SN02 3D191 - B1 through H1

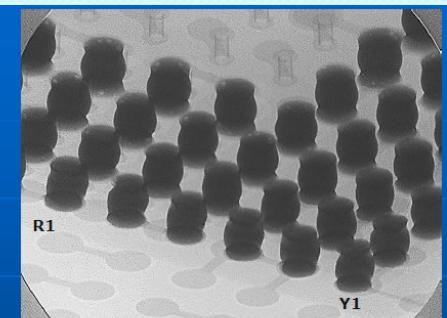


Figure 9  
SN02 3D191 - R1 through Y1

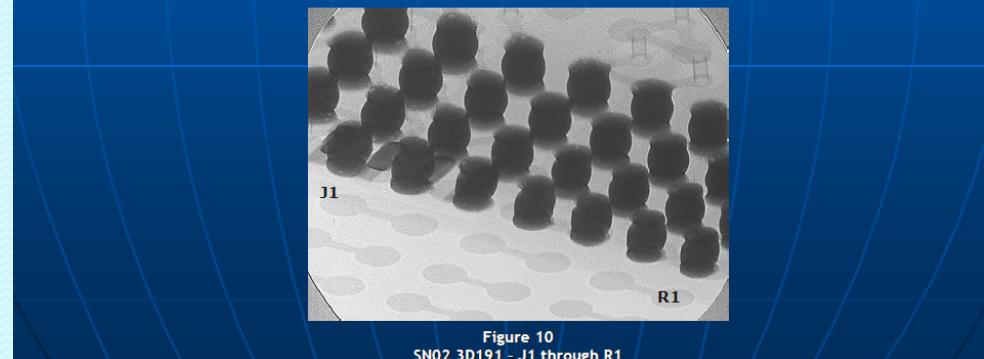


Figure 10  
SN02 3D191 - J1 through R1



Jet Propulsion Laboratory  
California Institute of Technology

# 3D Stack

## X-section after TC

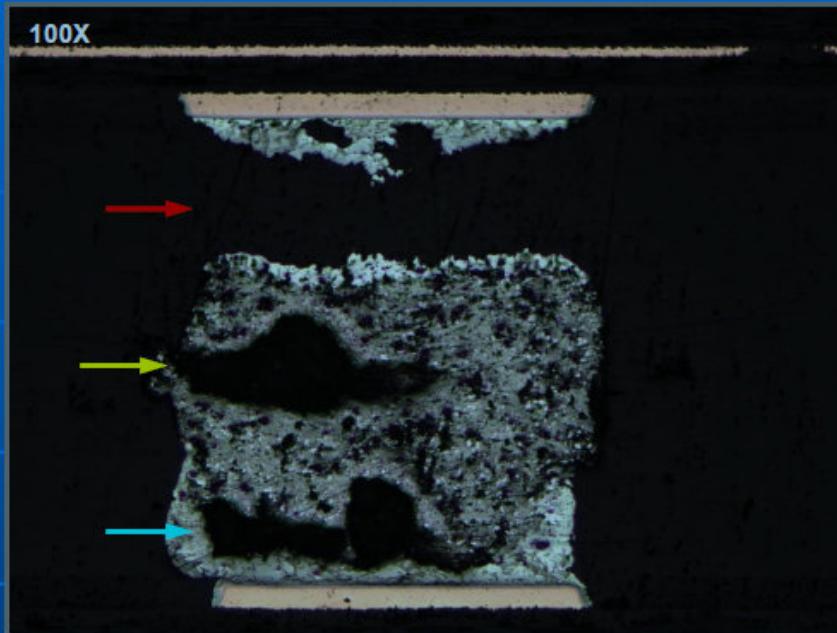


Figure 120  
SN02 3D191 B1 - Bright Field Light

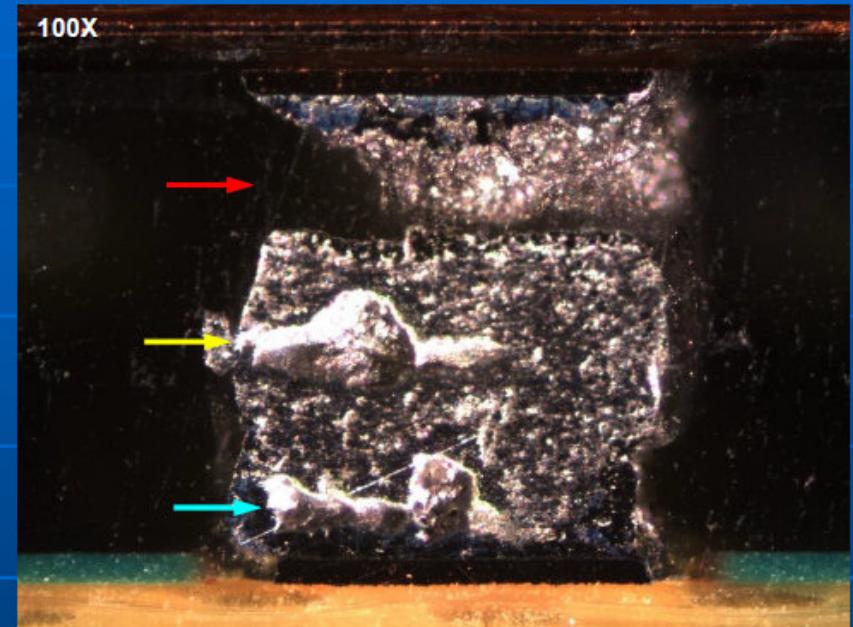
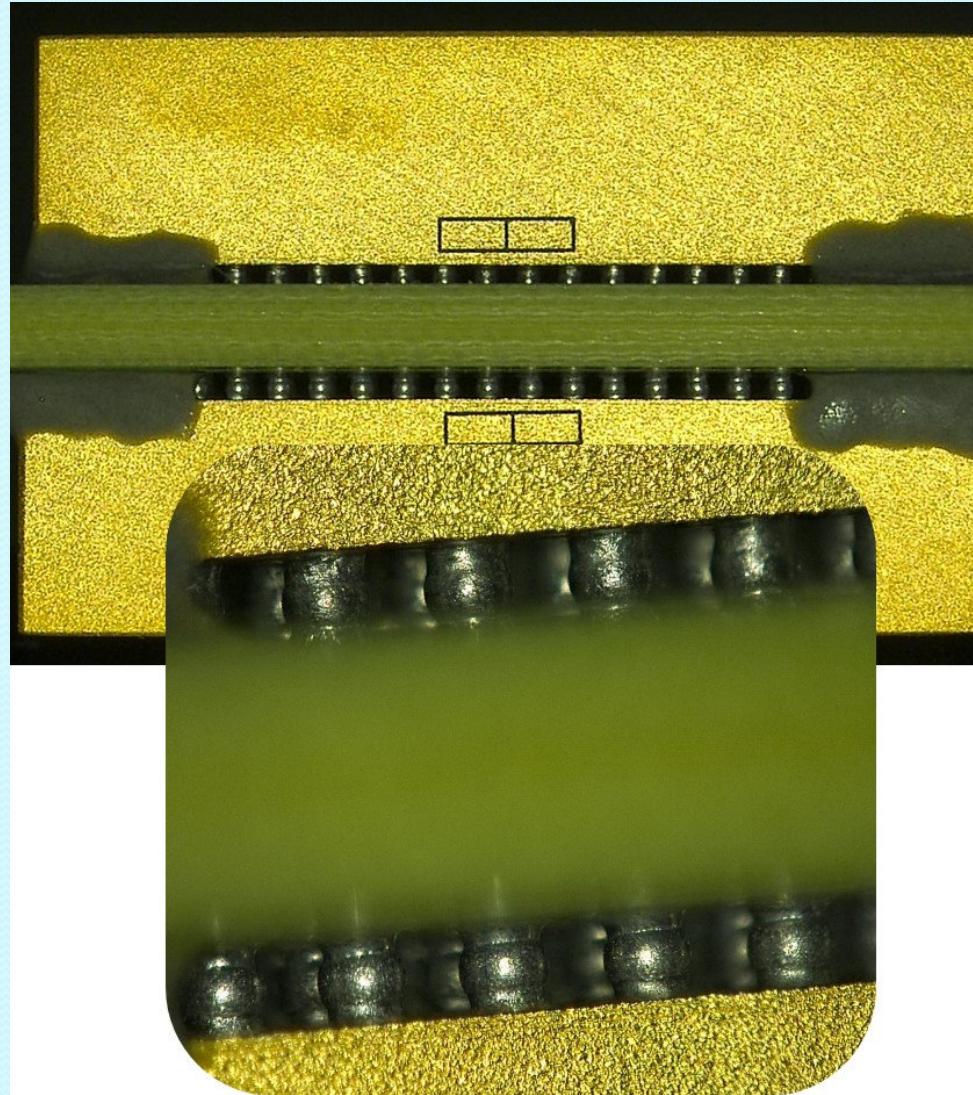


Figure 121  
SN02 3D191 B1 - Dark Field Light



Jet Propulsion Laboratory  
California Institute of Technology

# 3D Stack Double-sided



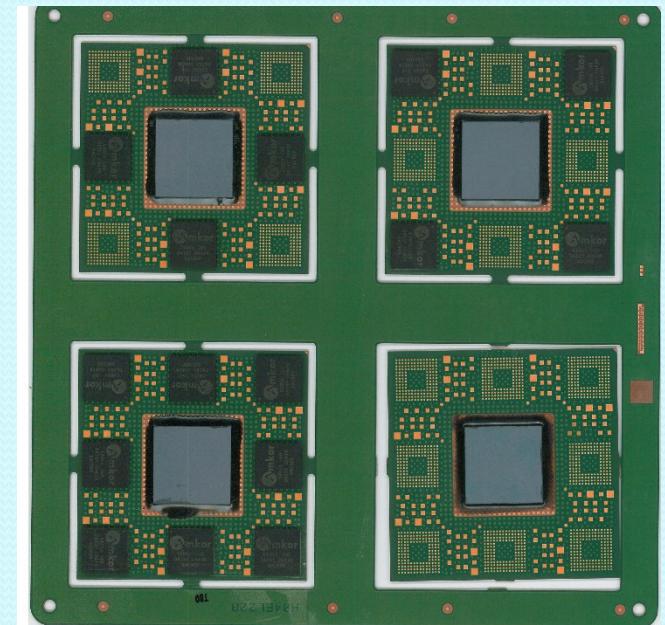
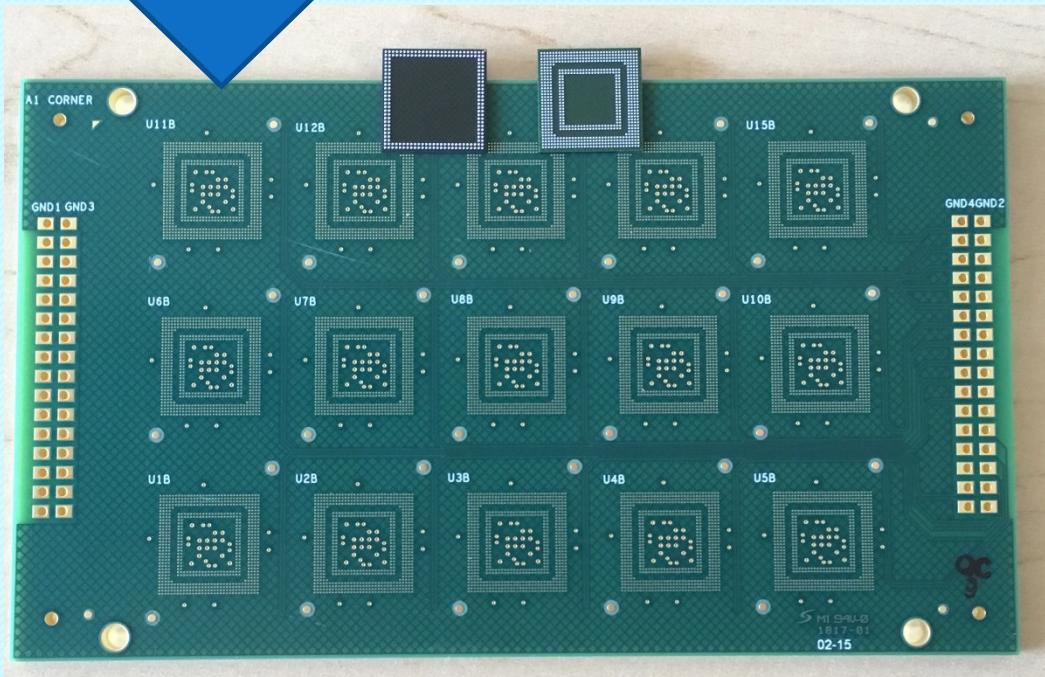
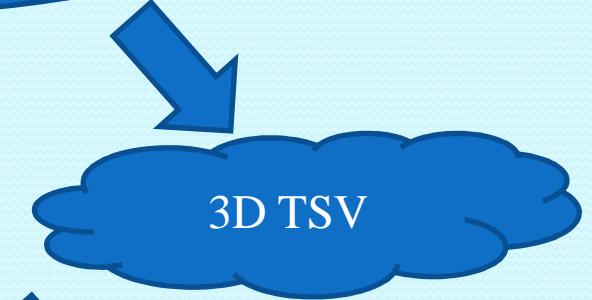
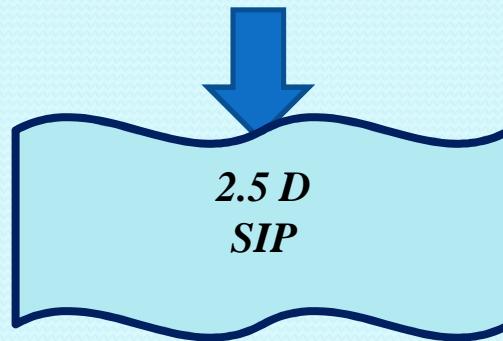


Jet Propulsion Laboratory  
California Institute of Technology

## TMV/TSV Packaging Status



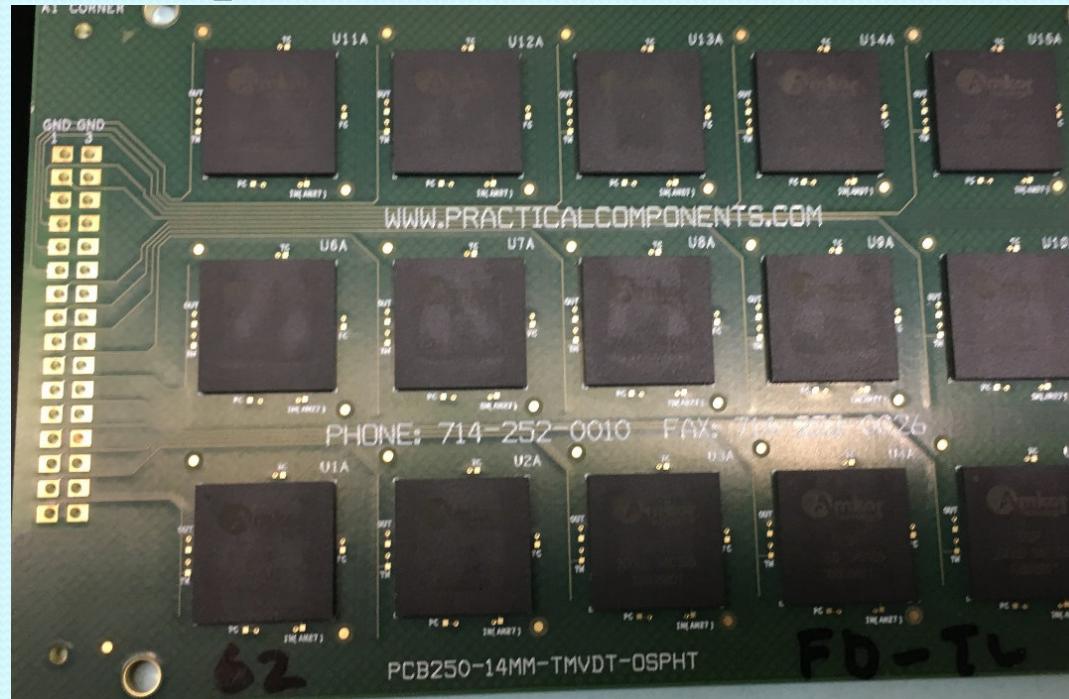
Through Mold Via (TMV)





# 3D TMV

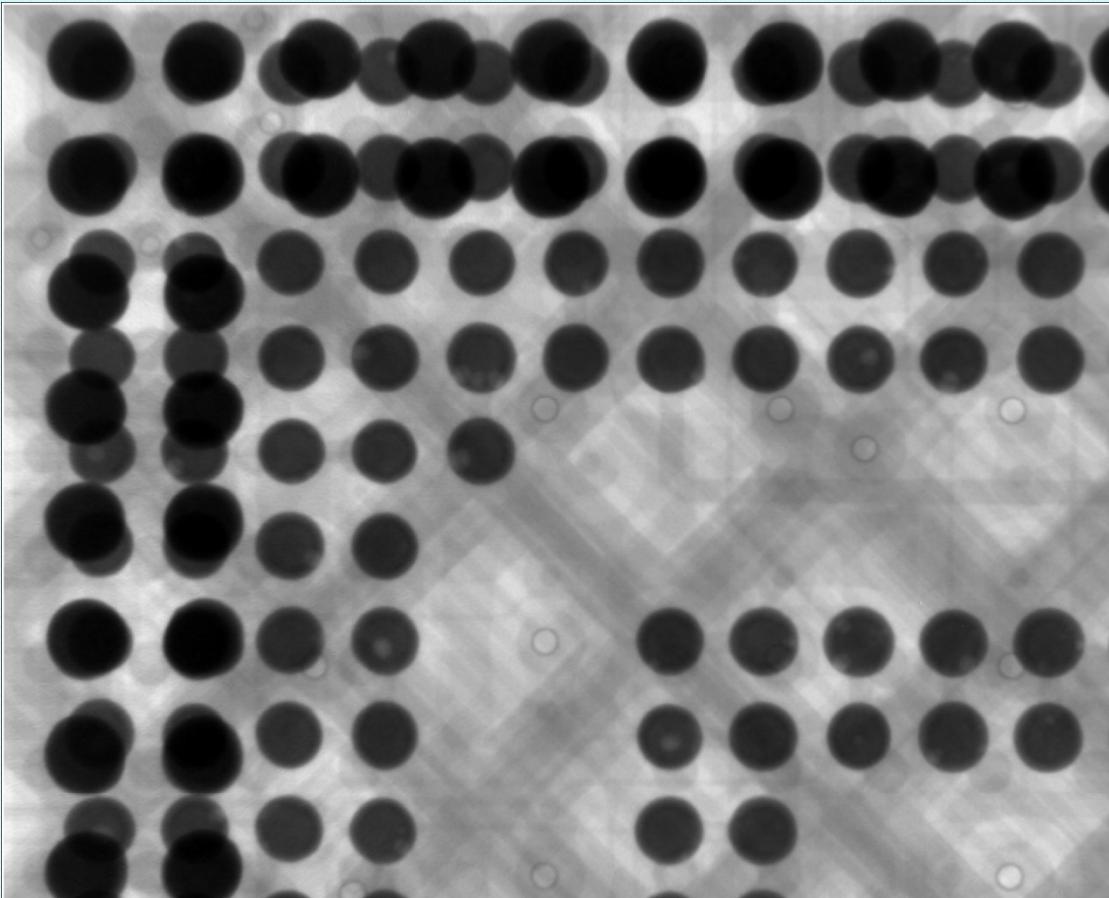
- Assembled ten (10) 3DTMV, 9-15 bottom/top parts
- Three assembly styles: Pre-stack, use solder paste for both bottom/top, use solder paste for bottom, flux for top
- No failures to 200 thermal cycles (-55/125C)
- NASA NEPP Report submitted





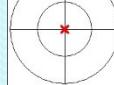
**Jet Propulsion Laboratory**  
California Institute of Technology

# 3D TMV



1.0mm

—

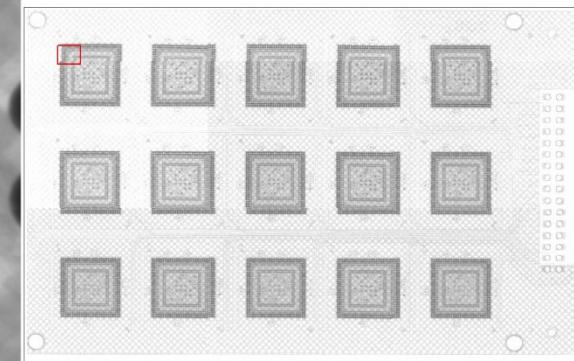


Tube voltage: 95 kV

Tube power: 1.97 W

Filter method used: None

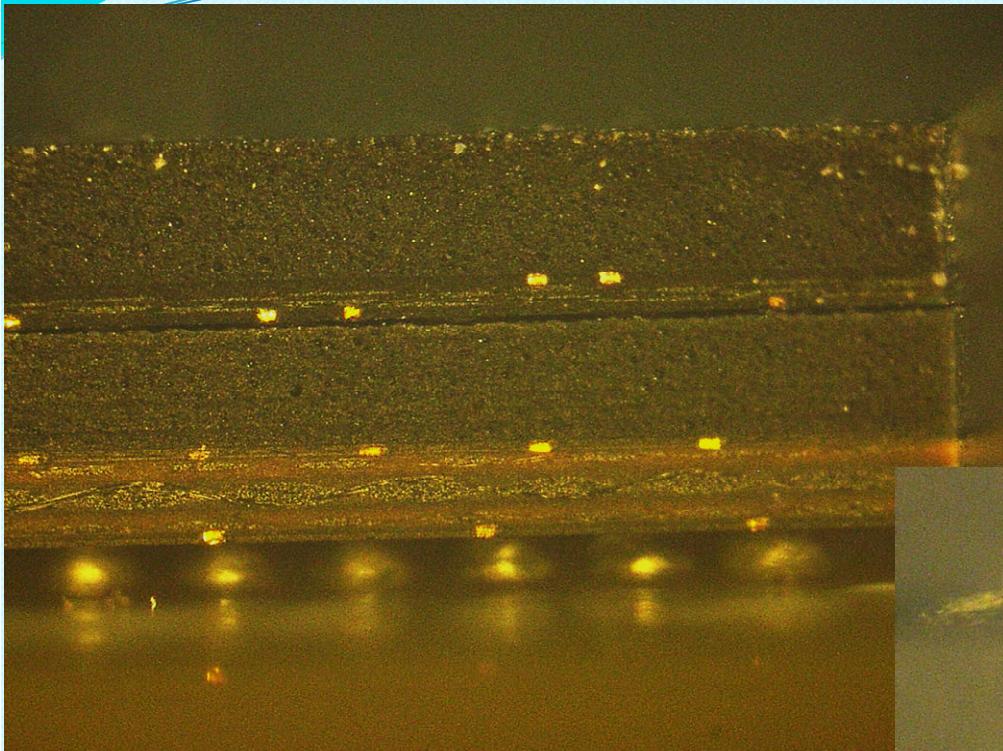
Averaging: 64 frames



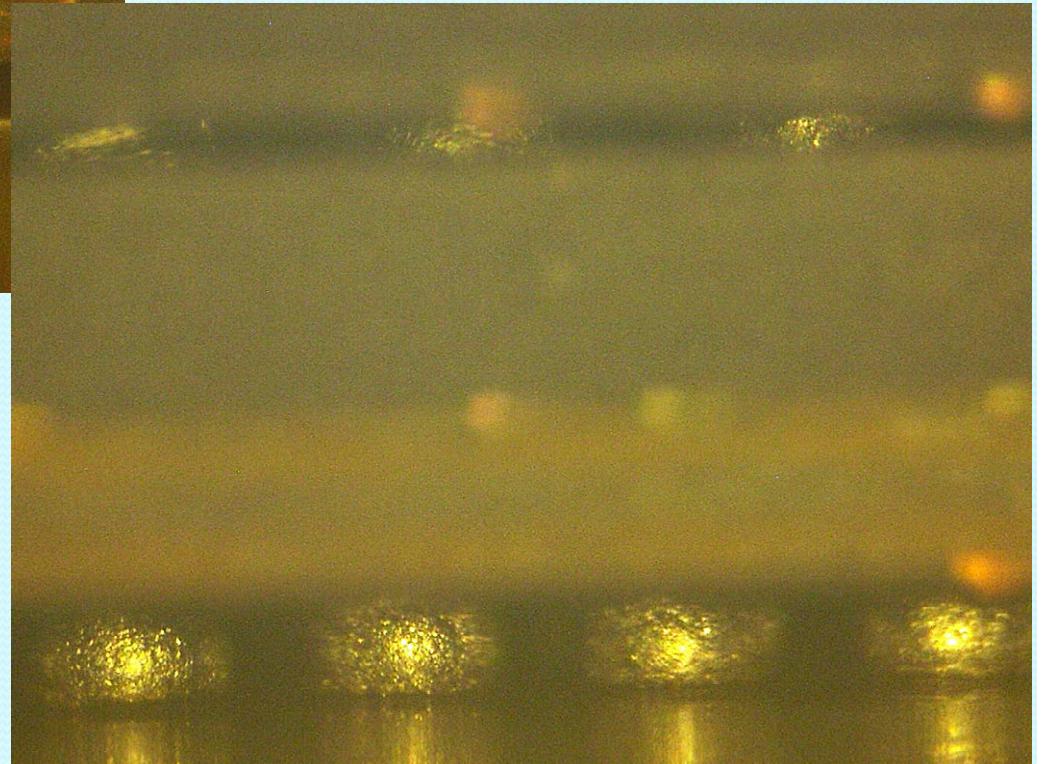


**Jet Propulsion Laboratory**  
California Institute of Technology

# 3D TMV after TC



**Bottom: Solder Paste**  
**Top: Solder Paste**

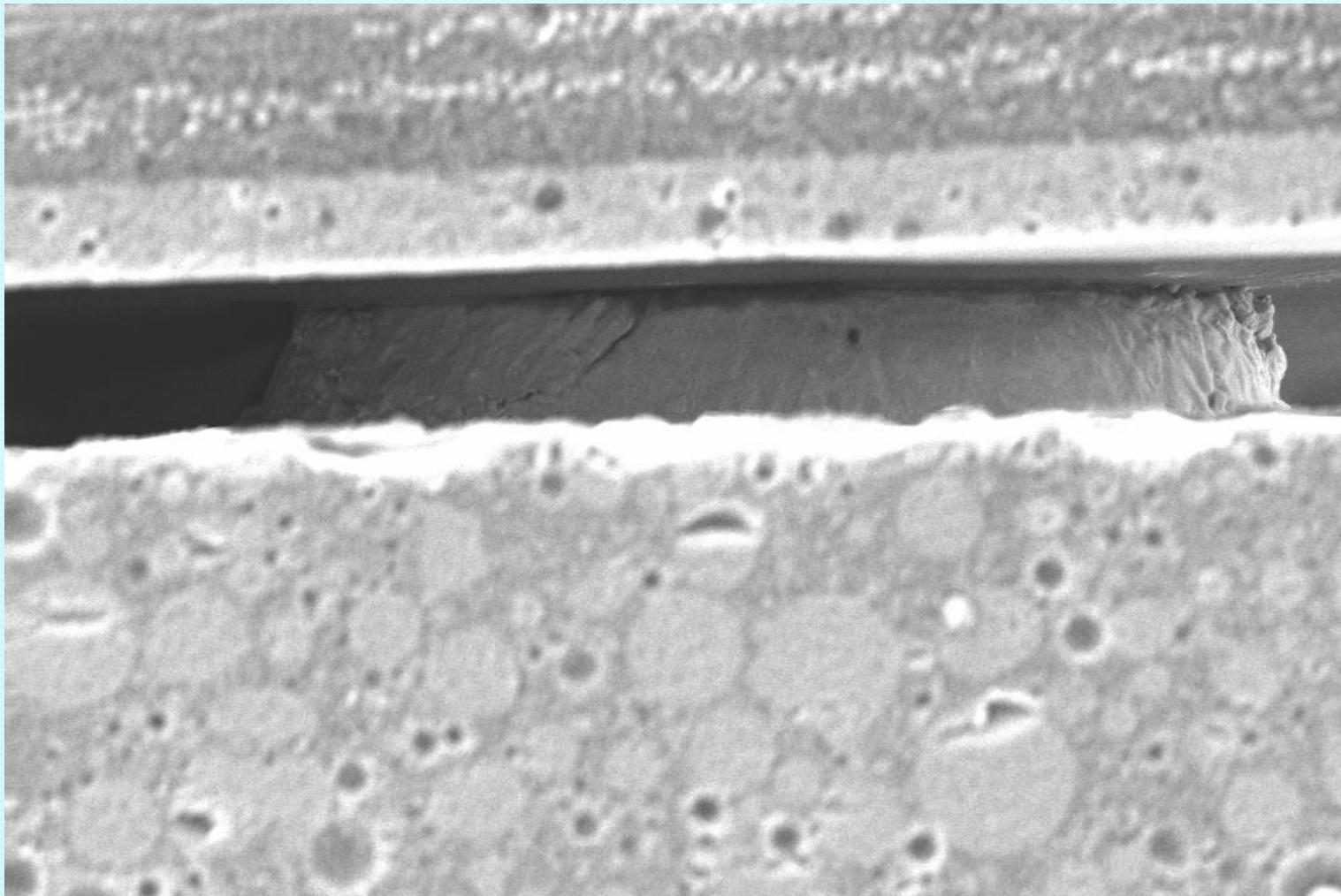


*Reza Ghaffarian/JPL/Caltech*



Jet Propulsion Laboratory  
California Institute of Technology

# 3D TMV SEM after TC/Cut



20  $\mu\text{m}^*$

EHT = 20.00 kV  
WD = 6.4 mm

Signal A = SESI  
Mag = 310 X

Date : 4 Jun 2018  
FIB Lock Mags = No



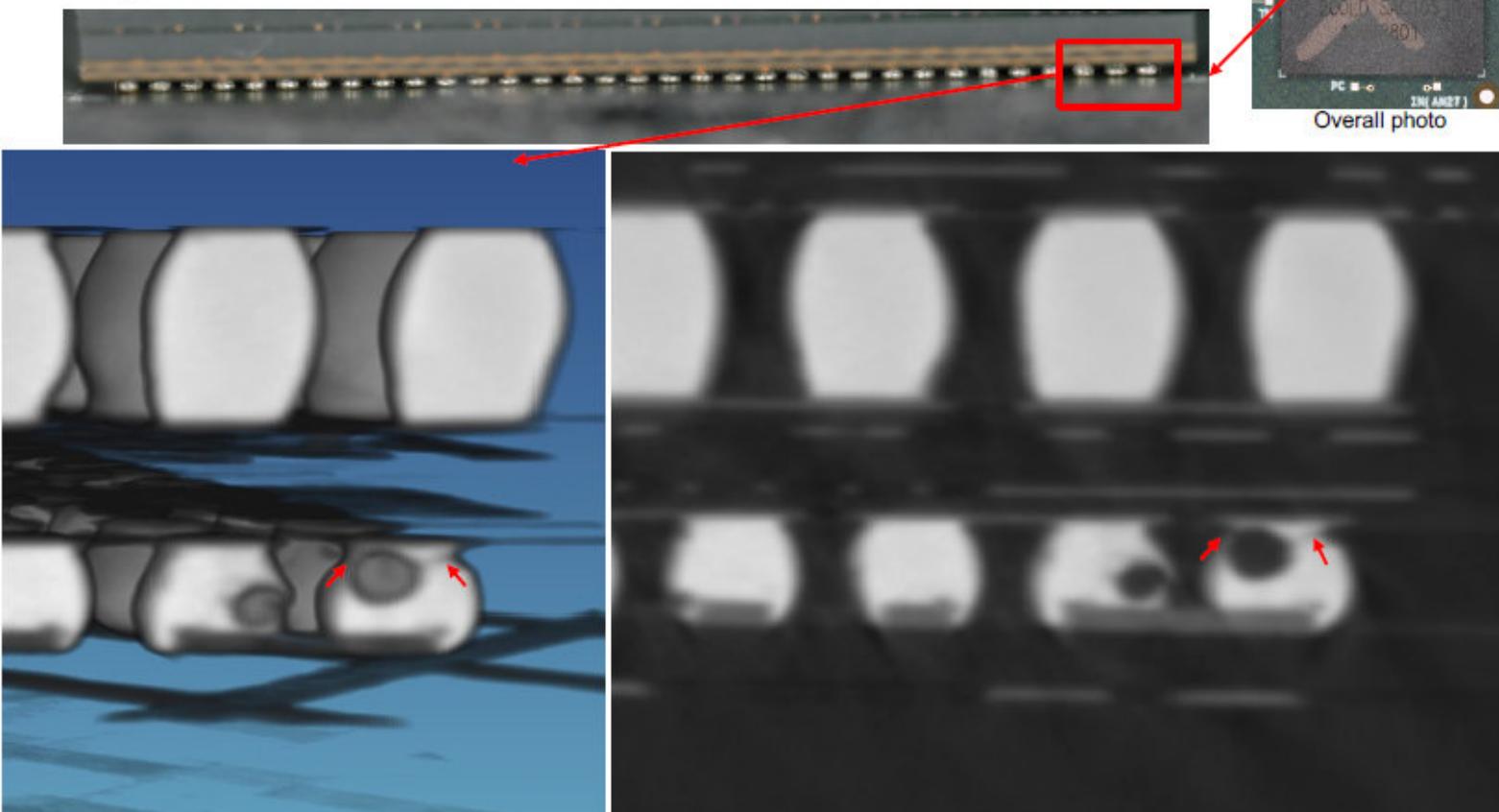


Jet Propulsion Laboratory  
California Institute of Technology

# 3D TMV

## 3D CT Scan after TC/Cut

Optical Photos Board SN50



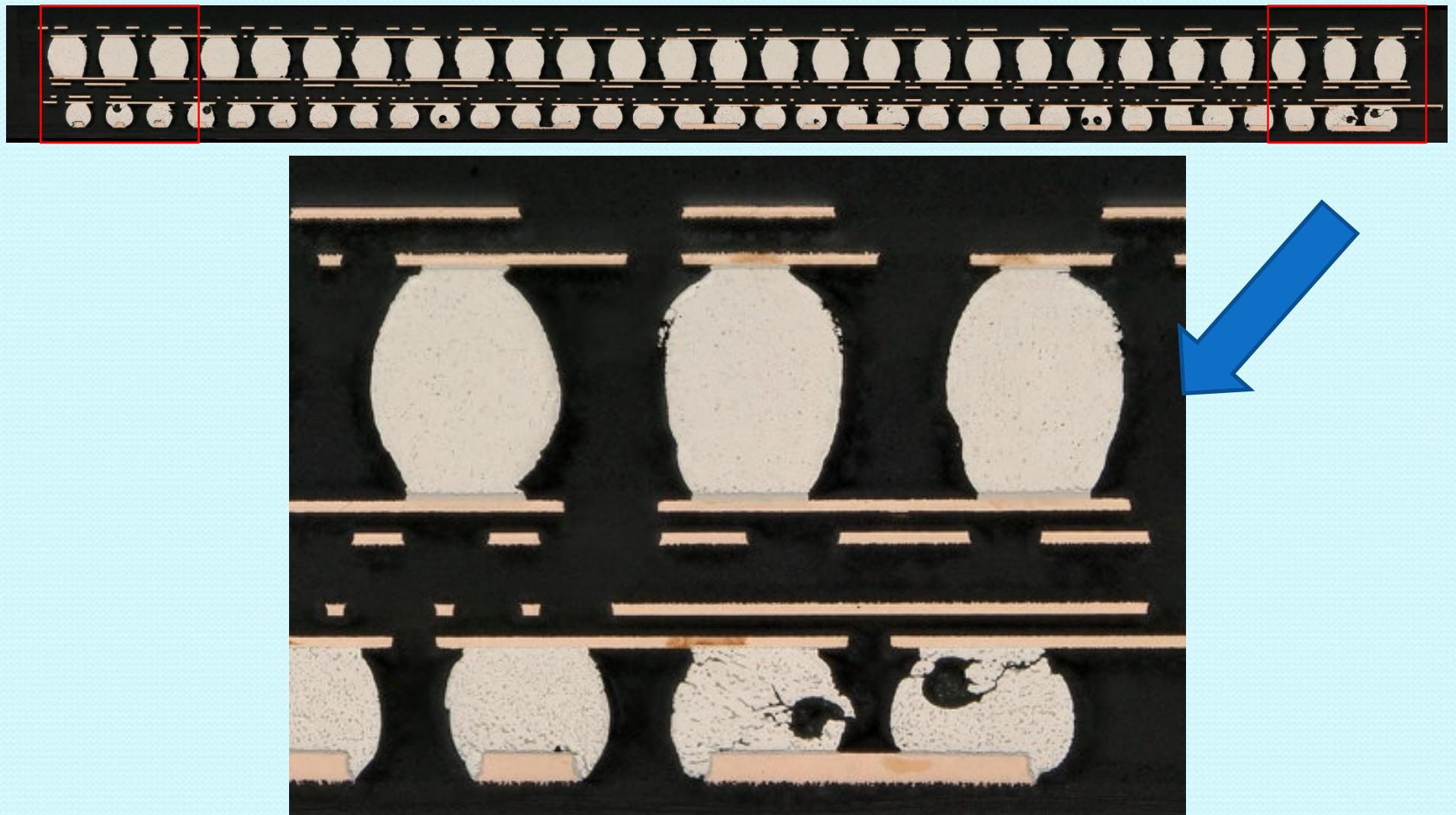
CT 3D cross section showing suspect crack in solder ball.

CT cross section showing suspect crack in solder ball.



Jet Propulsion Laboratory  
California Institute of Technology

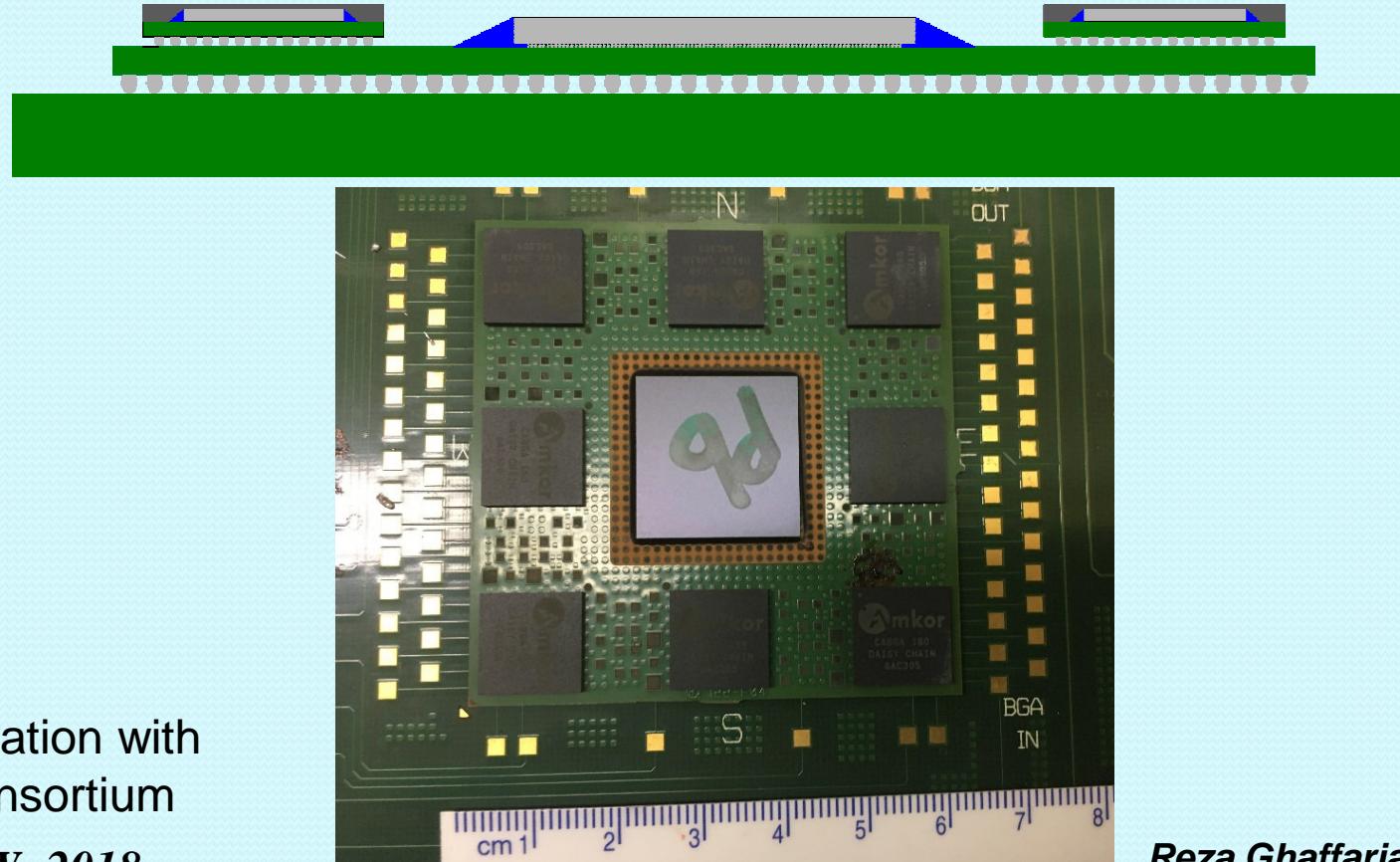
# 3D TMV X-section at 3D Scan





# SiP TC Evaluation\*

- Assembled 12 SIP includes CSP/FC
- Tin-lead and lead-free balls
- No failures to 200 thermal cycles (-40°C/125°C)



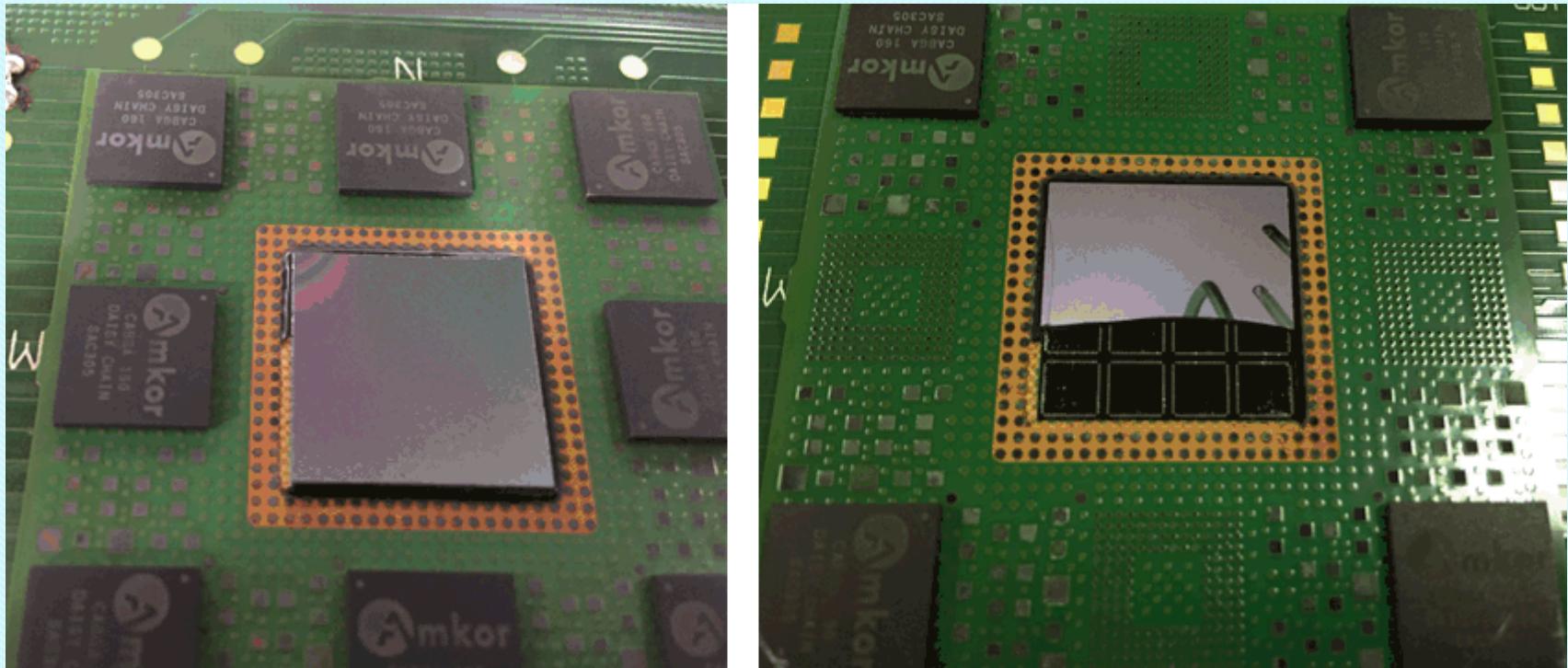
\* Collaboration with  
AREA Consortium  
**NEPP ETW- 2018**

*Reza Ghaffarian/JPL/Caltech*



# SiP TC Evaluation

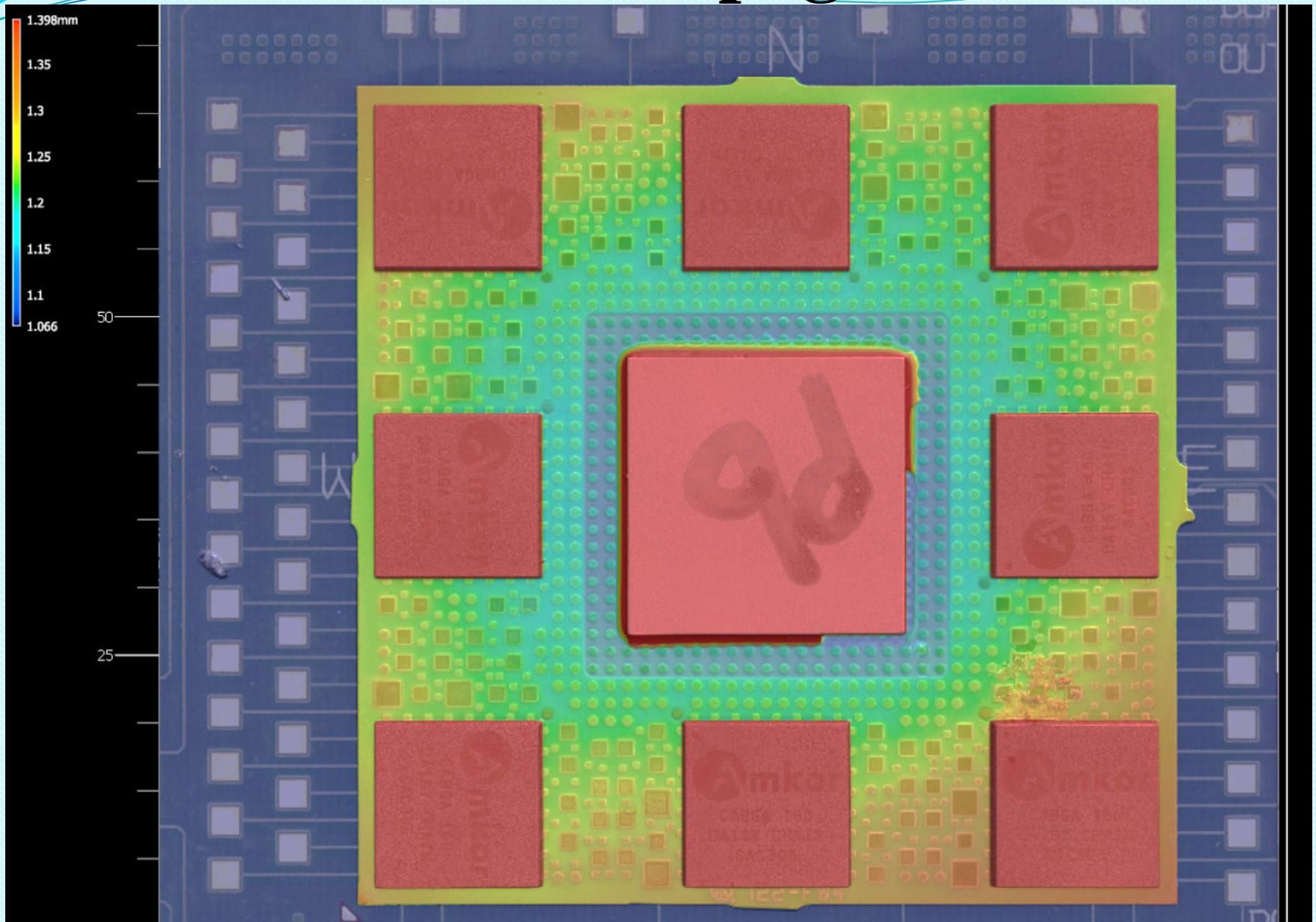
- Failures at higher cycles
- Early failures and standard failures for CSPs
- Failure due to warpage for FC





Jet Propulsion Laboratory  
California Institute of Technology

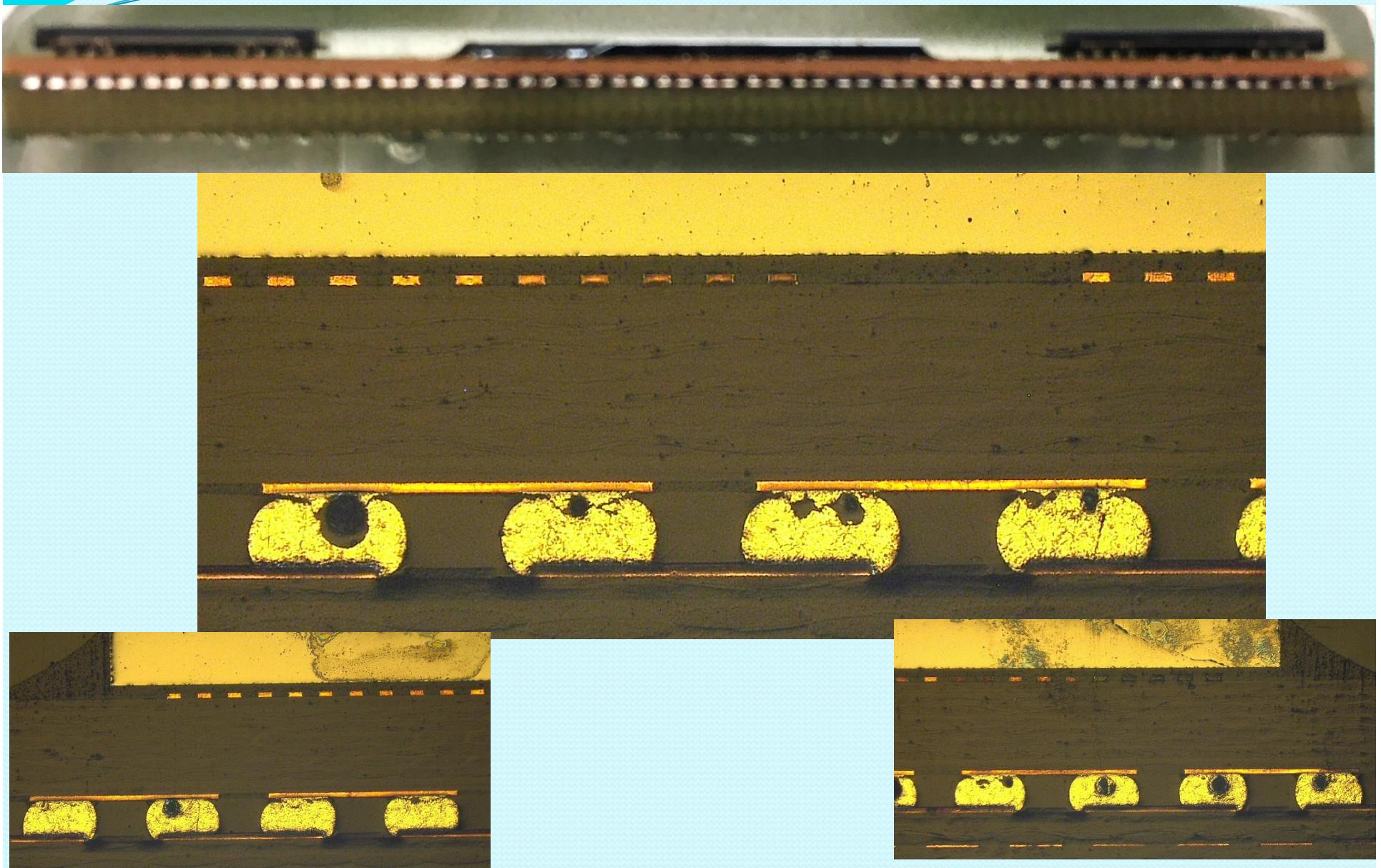
# Warpage for SiP





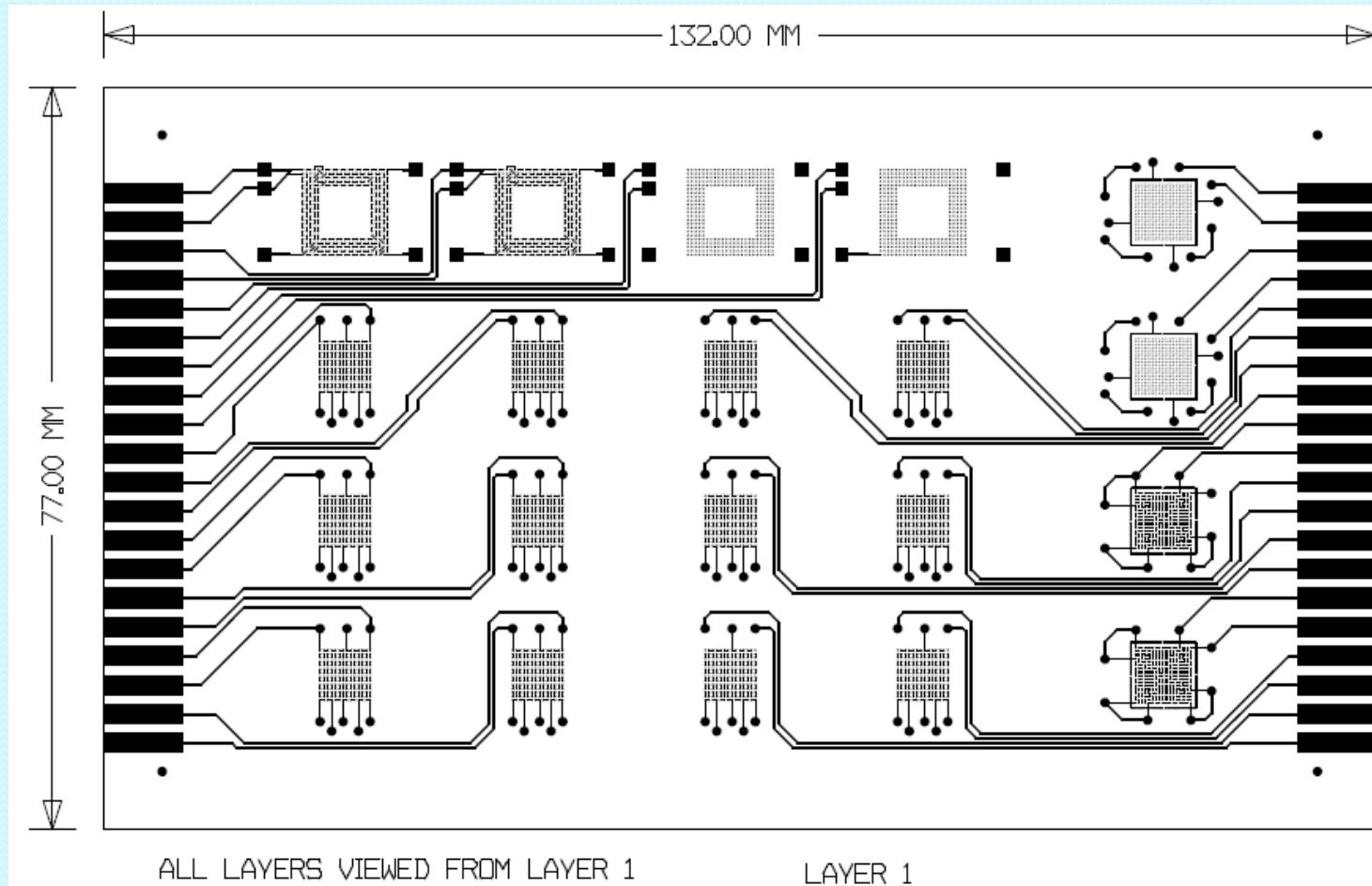
Jet Propulsion Laboratory  
California Institute of Technology

# BGA Failure in SiP





# WLP & 3D TSV TC Evaluation



- Option 1:** Modified WLP TSV to enable PCB manufacturing
- Option 2:** Use interposer for TC



# Summary

- Packaging technologies
  - Standard to WLP and 3DTSV
- NEPP evaluated reliability of numerous packages
  - FCBGA, FPBGA, 3D stack, WLP, SiP, and 3D TSV
  - Presented results of numerous TC evaluation
- No failure to 200 TC cycles ( $-55^{\circ}/100^{\circ}\text{C}$ )
  - FCBGA1924, PBGA896, FPGA, 3D stack
  - No failure condition verified by daisy-chain or X-section
- Failure to 200 TSC cycles ( $-65^{\circ}/150^{\circ}\text{C}$ )
  - FPBGA 432 I/O, 0.4 mm pitch failed near 100 cycles
- No failure of TMV assemblies ( $-55^{\circ}/125^{\circ}\text{C}$ )
  - All paste at board, but solder paste or flux on the top
  - Pre-stack with paste and then solder onto board
- No failure of SiPs ( $-40^{\circ}/125^{\circ}\text{C}$ )
  - Effect of top stack on lower failure initiation observed at higher cycle
  - Various failures including flip-chip at higher cycles
- Design/Assembly of WLP/FOWLP on standard PCB is challenging. Interposer needed
- NEPP Test Report on FCBGA/3D stack is on NEPP Website
- NEPP Report for TMV/SiP is being released



**Jet Propulsion Laboratory**  
California Institute of Technology

# Acknowledgment

The research described in this publication is being conducted at the Jet Propulsion Laboratory, California Institute of Technology, under a contract with the National Aeronautics and Space Administration. Copyright 2018 California Institute of Technology. U.S. Government sponsorship acknowledged.

The author would like to acknowledge the support of the JPL team and industry partners. The author also extends his appreciation to the program managers of the National Aeronautics and Space Administration Electronics Parts and Packaging (NEPP) Program, including M. Sampson, K. LaBel, Dr. D. Sheldon, Dr. J. Evans, and J. Pellish for their support and continuous encouragement.

<http://nep.nasa.gov>

**Thank  
You!**

